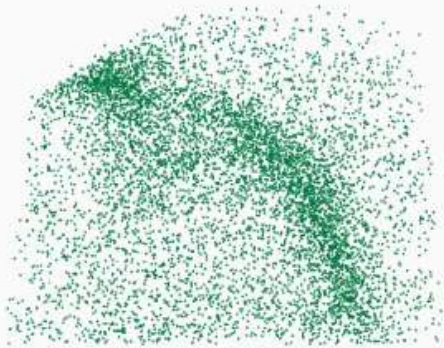


Atom Probe Tomography of Oxidation processes in NiAlCr-alloys

Torben Boll

20 nm



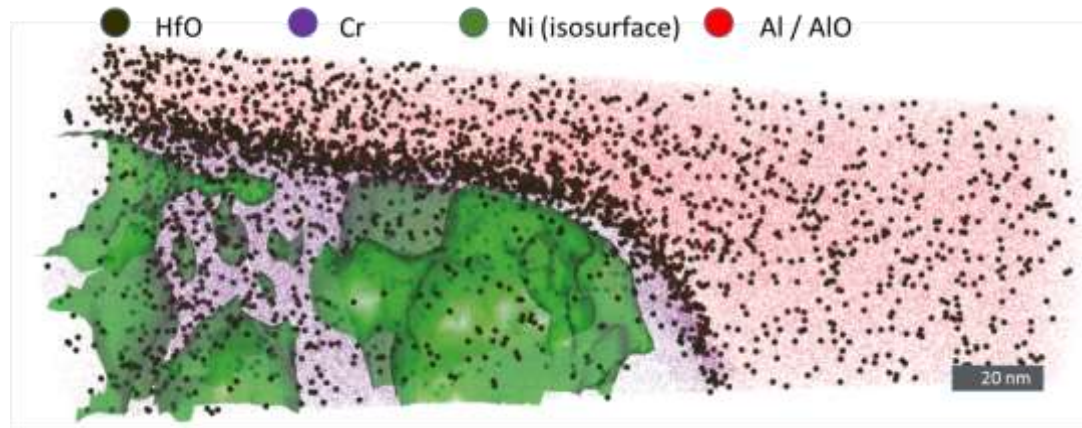
Zr at a grain boundary in Al_2O_3

- Field Ion Microscopy
- Atom Probe Tomography
- Investigated Materials @ KIT
- Oxidation of NiAlCr
- Outward diffusion through Al_2O_3

BAM Berlin 14.02.2018

What can APT do for me?

- 3D-information of a sample up to 200 nm laterally and up to 1000 nm in depth
- Mass to charge ratio: Chemical information
- Atomic resolution (<0.1 nm) can be achieved in z-direction (in lateral directions 0.5 nm are typical)

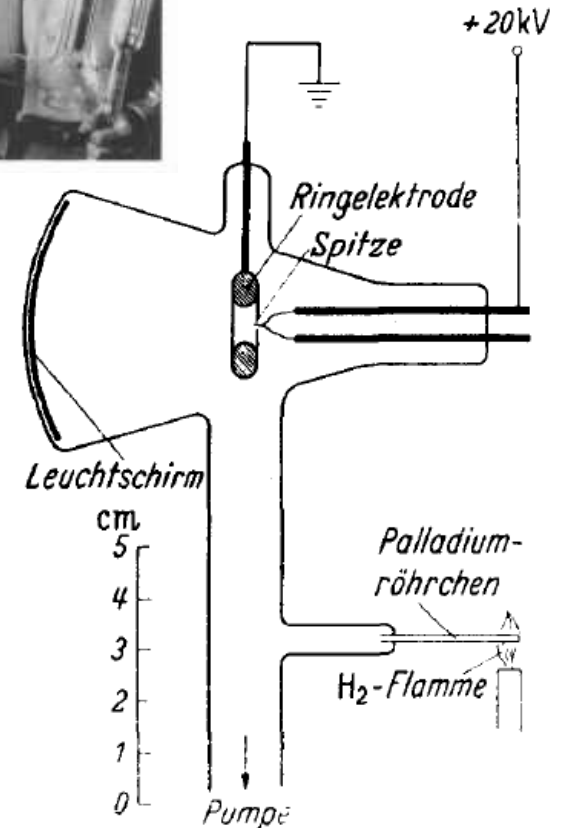


History

- 1951** Field Ion Microscope: Atomic resolution was achieved the first time in October, 17th 1955.
- 1967** Chemical Analysis by time of flight measurement in Atom Probe Field Ion Microscope (APFIM)
- 1989** Position Sensitive Atom Probe
- 2001** Local Electrode Atom Probe (LEAP)
- 2013** Installation of LEAP 4000X HR at KIT
- 2018** Installation of Laser Assisted Wide Angle Atom Probe (LAWATAP) at KIT

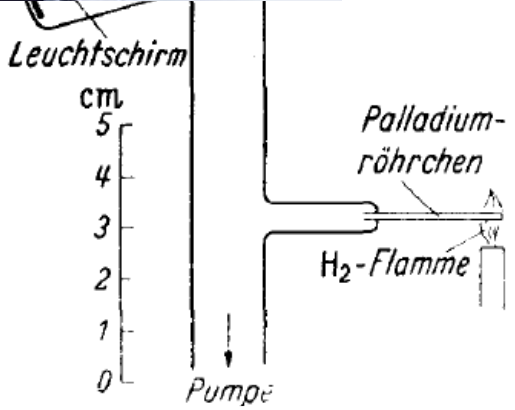


Erwin Wilhelm Müller
(*1911, † 1977):



History

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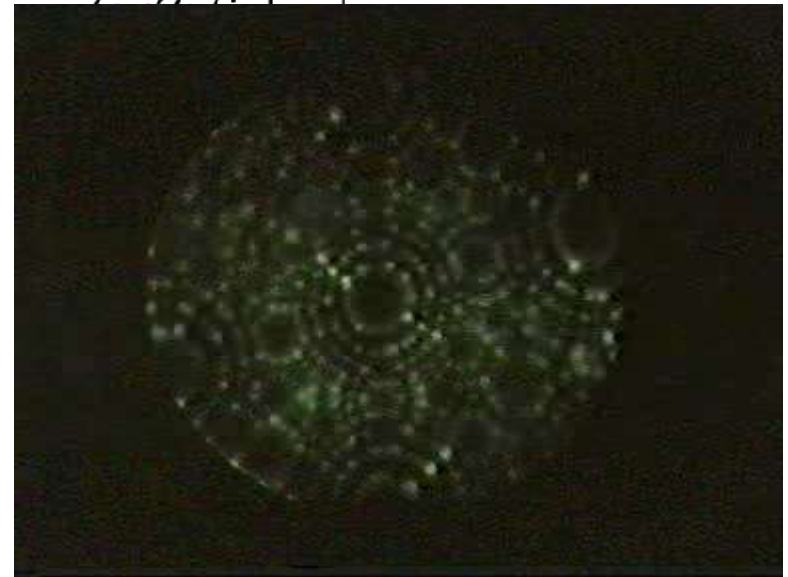
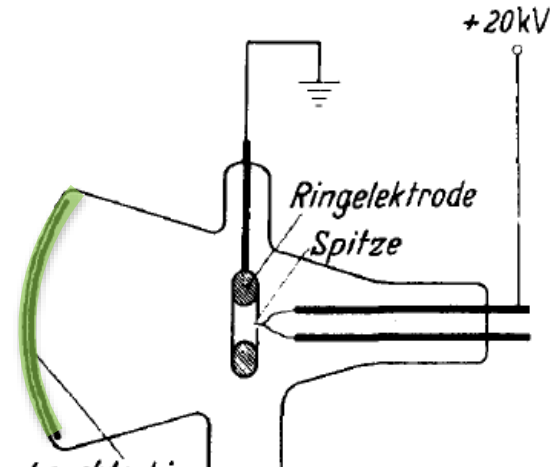


Field Ion Microscopy

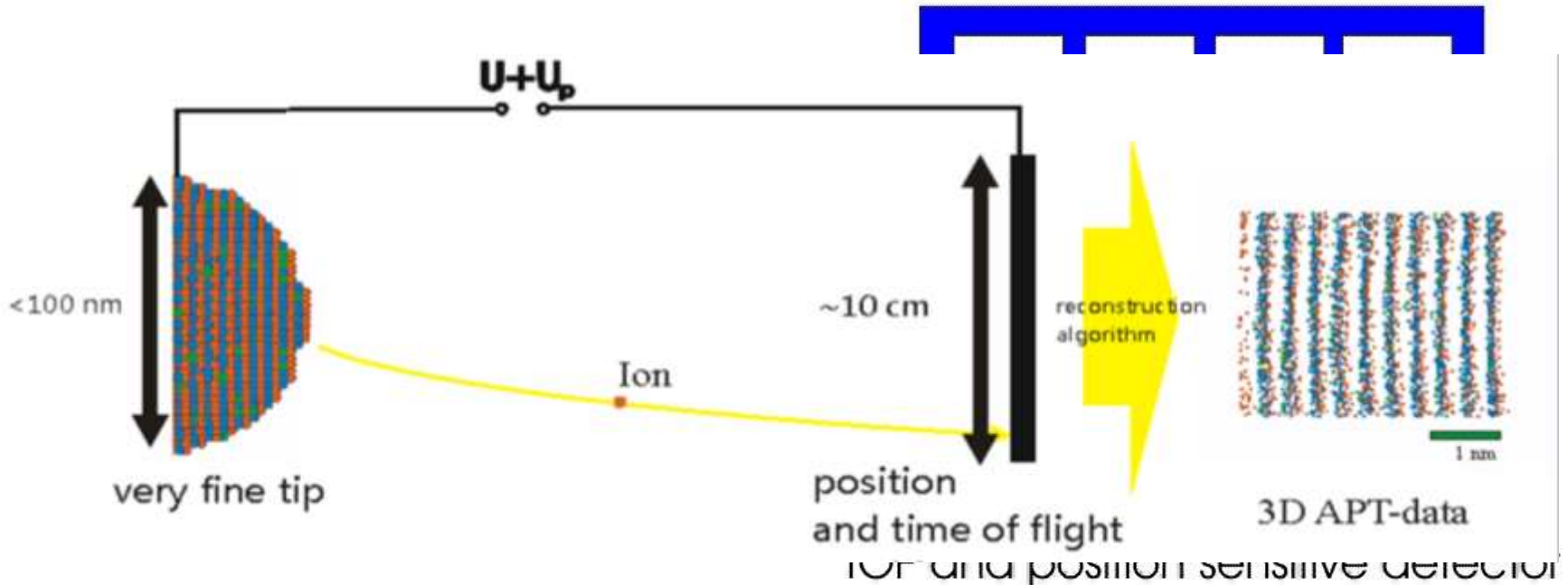


Video: B. Färber (Göttingen)

- Image gas ionizes on tip surface
- Ions are accelerated towards the screen
- Kinks (i.e. atoms) are imaged on the phosphorous screen
- If voltage is increased, tip atoms are evaporated, the image changes



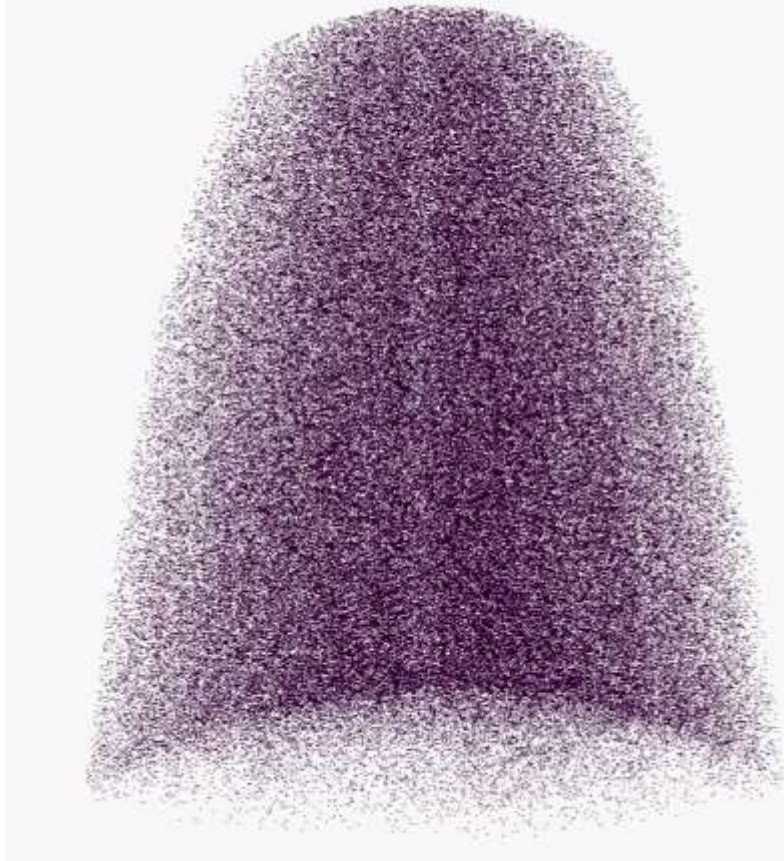
Atom Probe Tomography (APT)



- High field applied, almost strong enough to evaporate atoms
- Additional pulse (laser or voltage): Atom is evaporated
- From the flight time the mass to charge ratio can be calculated
- (x,y)-dimension is known from the detector, z is determined from the sequence of arrival

Resolution

Exp. APT of W (side view)

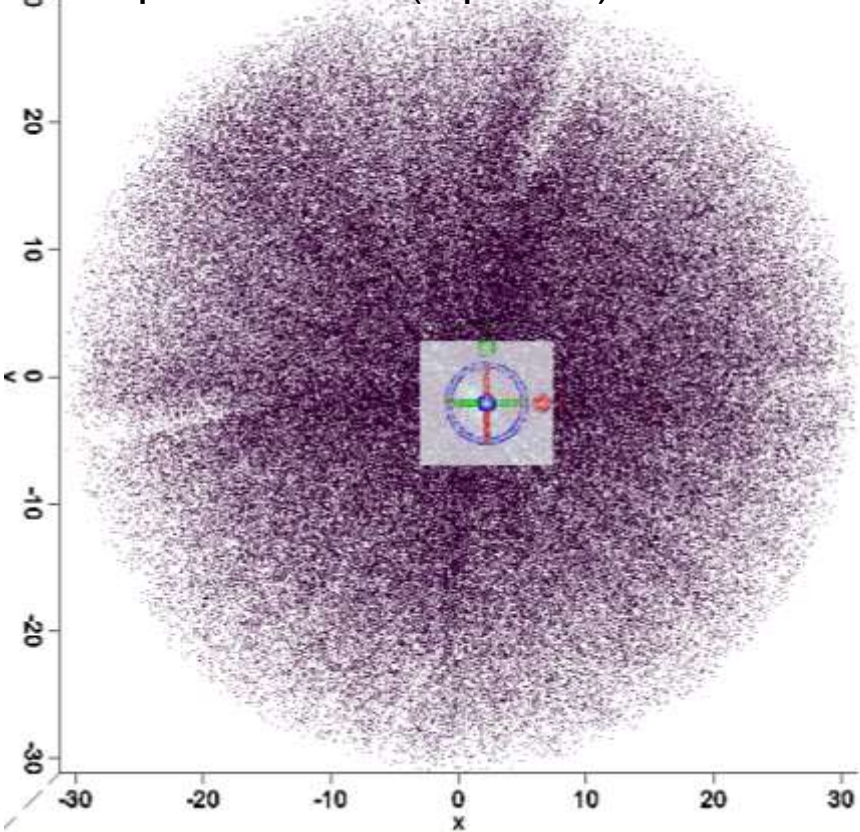


10 nm

- 3D- Atom Probe Tomography (APT) data often has atomic resolution in z-direction (crystallographic information)

Resolution

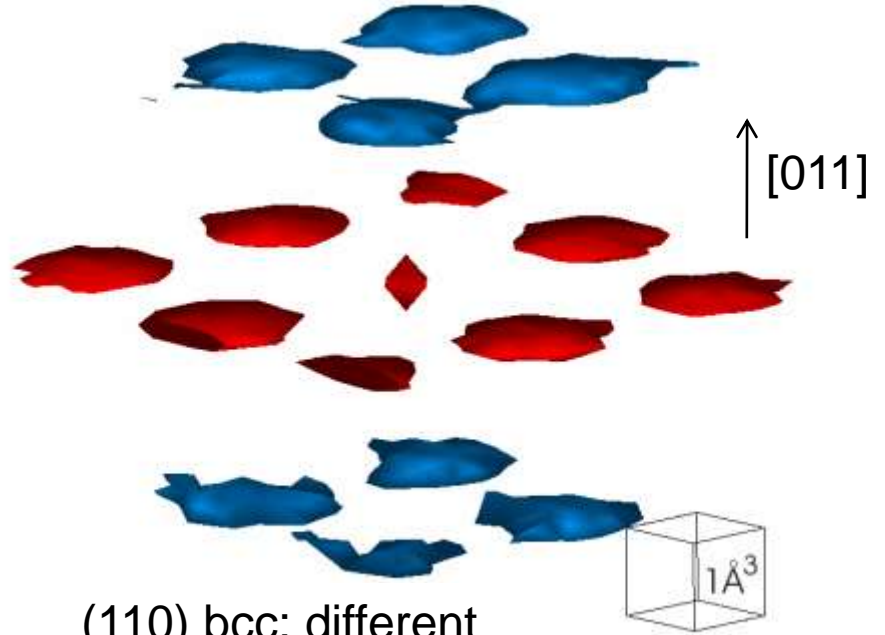
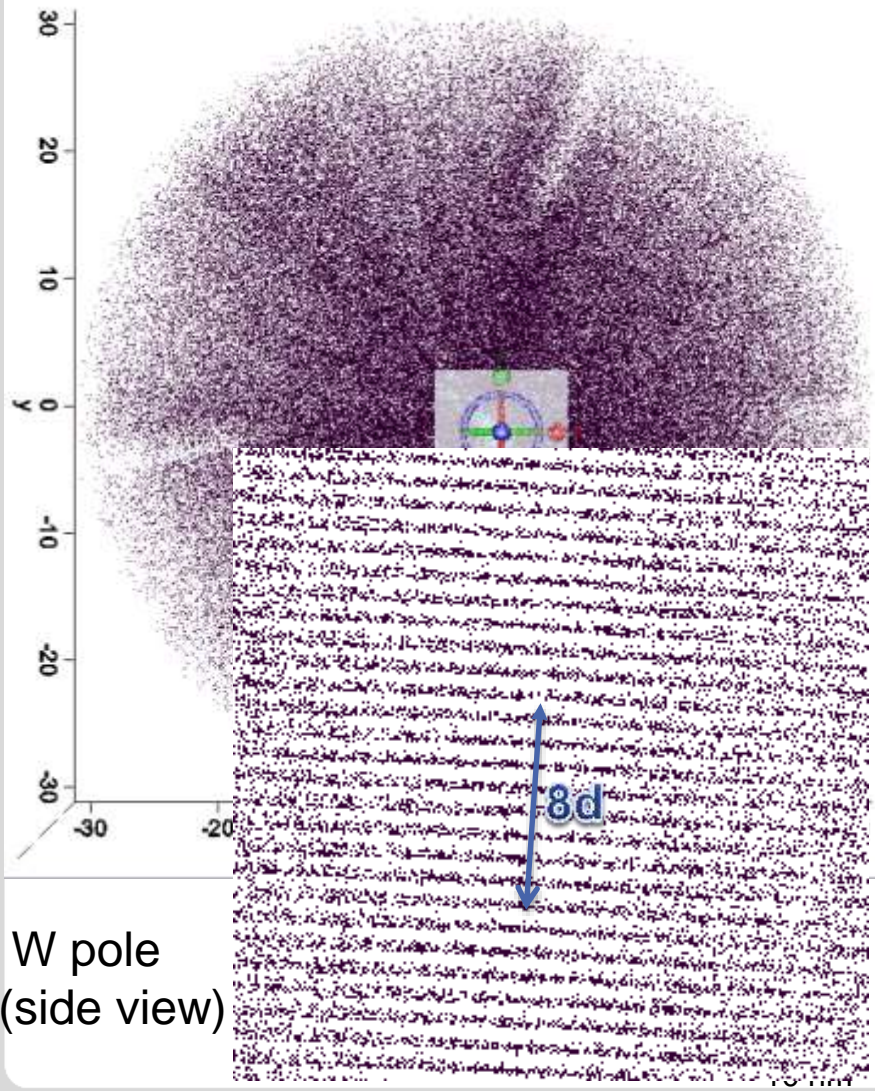
Exp. APT of W (top view)



10 nm

3D- Atom Probe Tomography (APT) data often has atomic resolution in z-direction (crystallographic information)

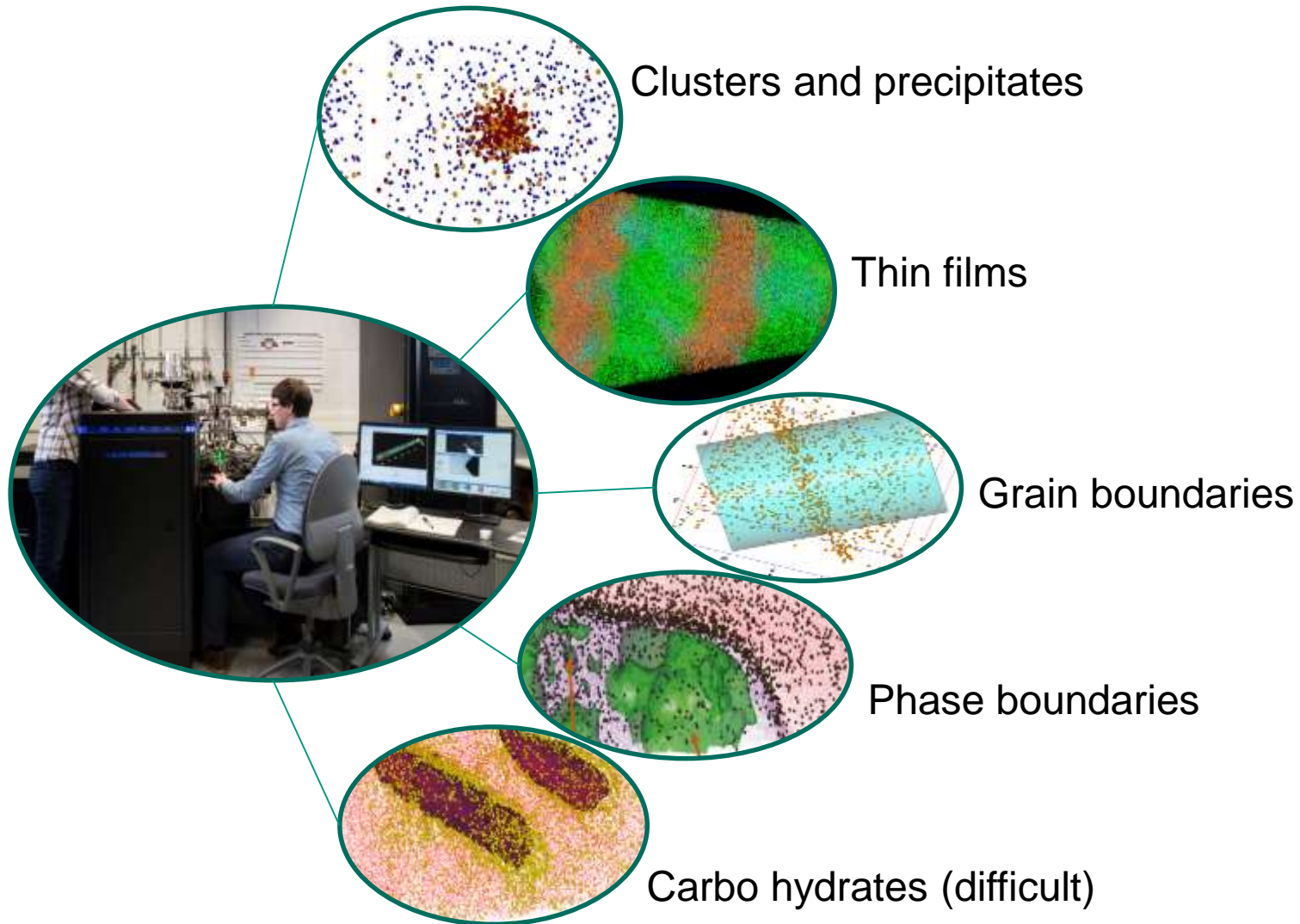
Resolution



(110) bcc: different planes emphasized by color

But often the resolution is not good enough -> data has to be processed to obtain this information

What can APT do for me?



Sample preparation: options

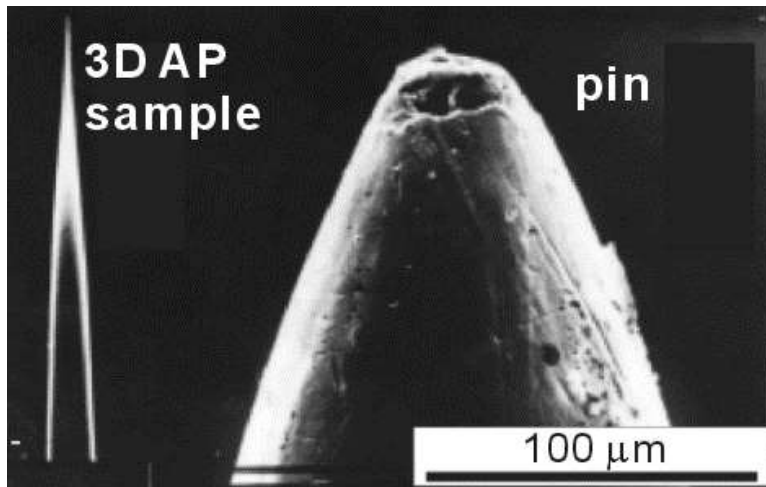
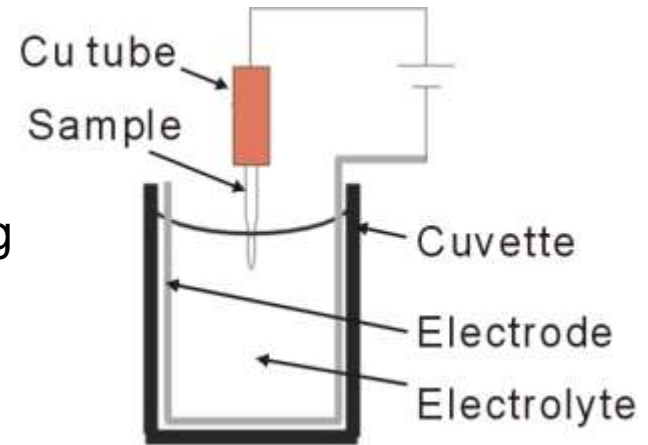


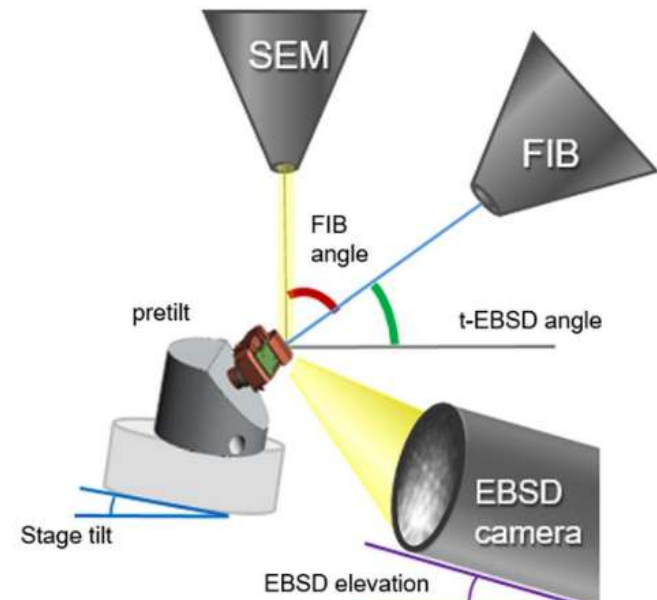
Image: B. Färber (Göttingen)

Electropolishing



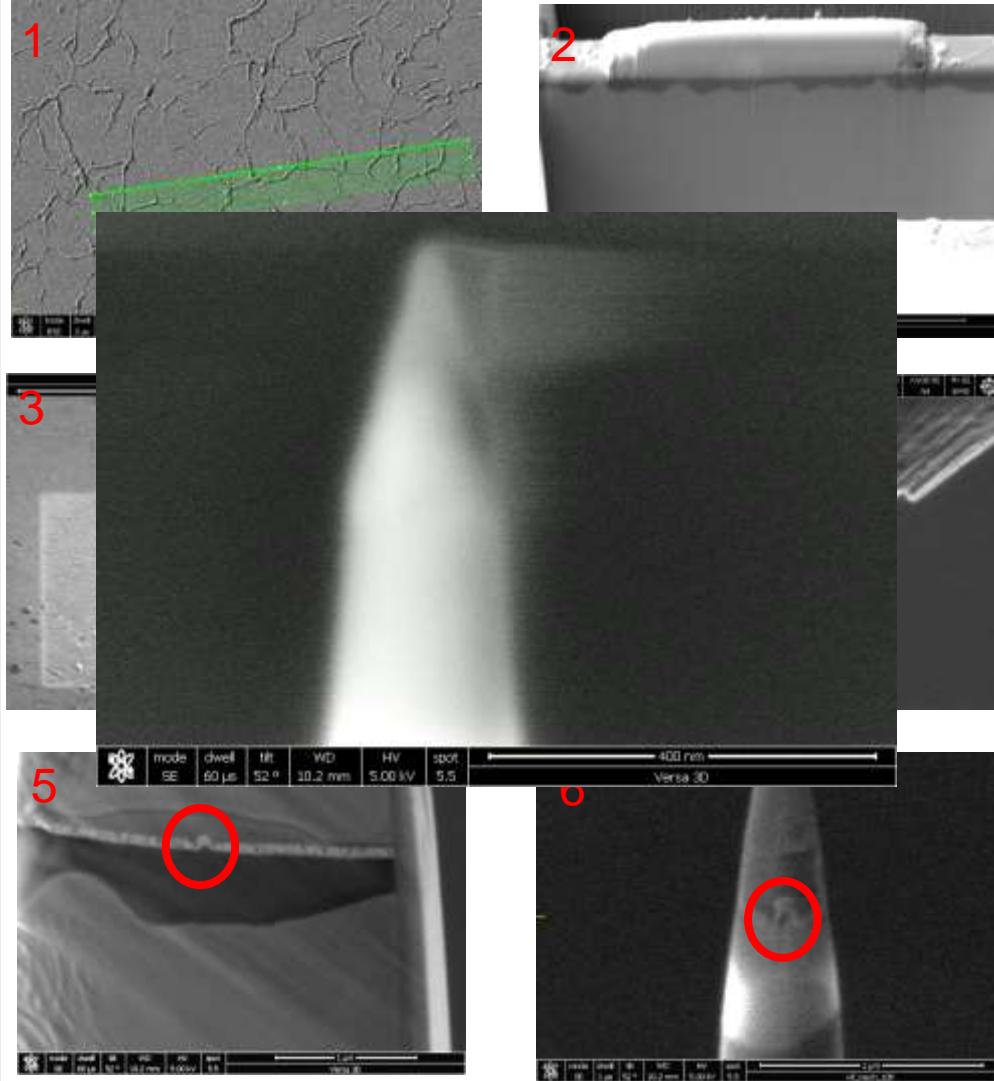
PhD thesis C. Wille 2010, Göttingen

Focused Ion Beam (FIB)



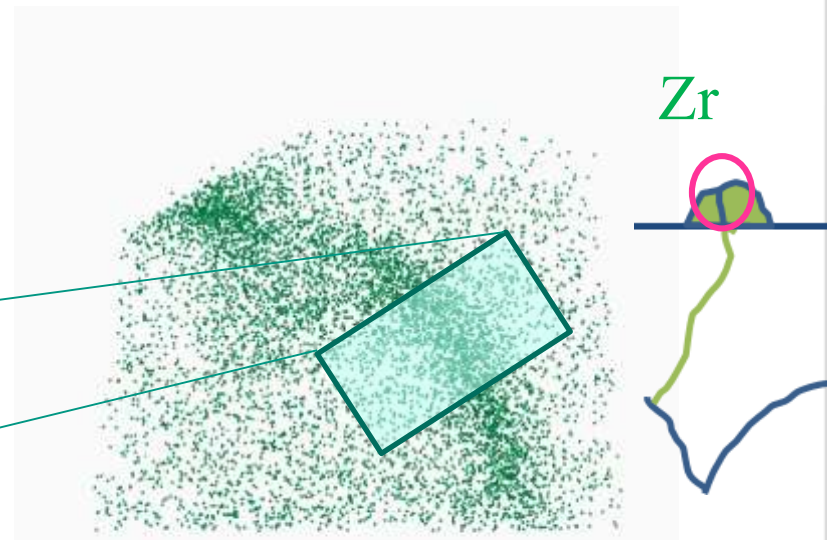
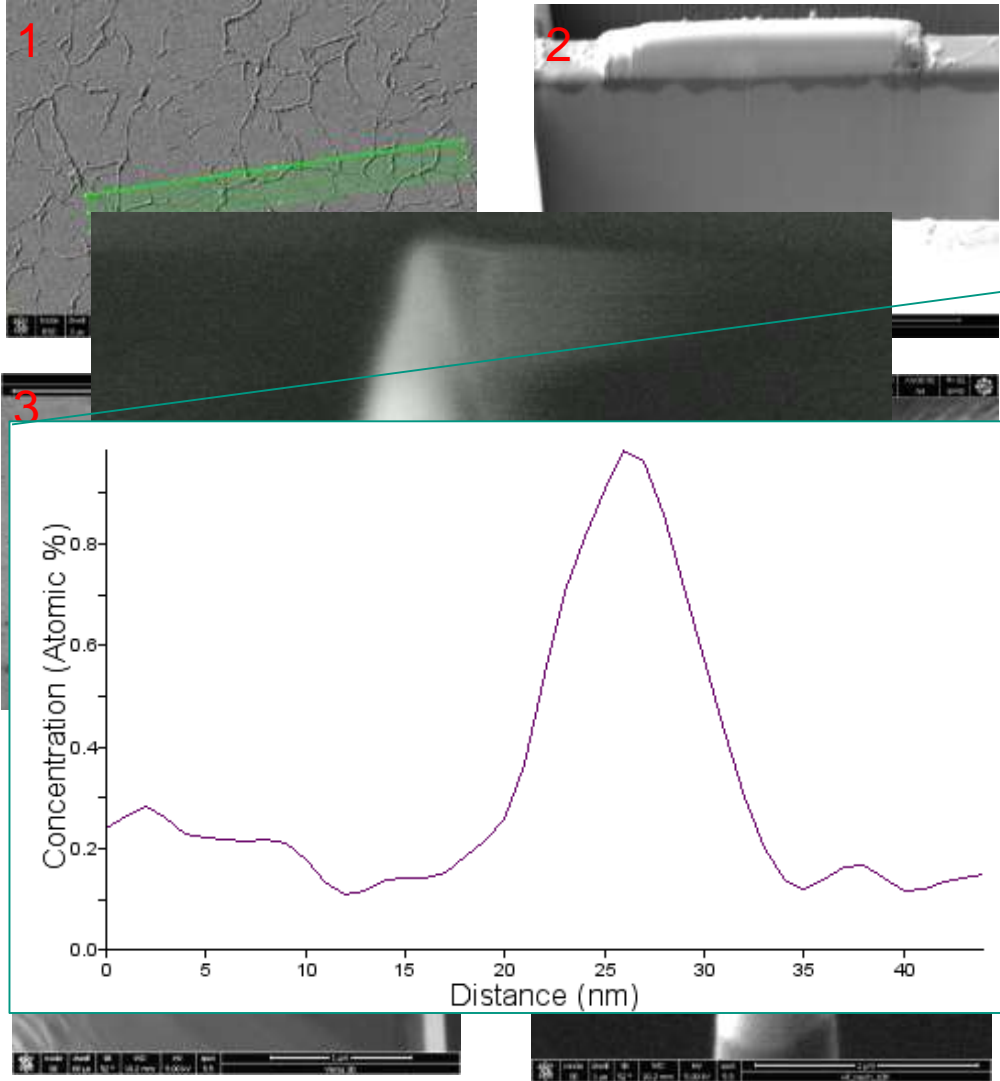
D. Larson et al, Microsc. Microanal. 2017

Sample preparation of surface features with FIB



- Protective sample coating (Au, Ag)
- Mark area with Pt, deposit 2 μm Pt on 2x10 μm
- Cut lamella
- Lift out
 - Attach lamella to OP
 - Cut lamella loose
 - Attach to micro tip
 - Cut loose
- Find feature (ridge)
- Annular milling at feature (ridge) while controlling position

Sample preparation of surface features with FIB



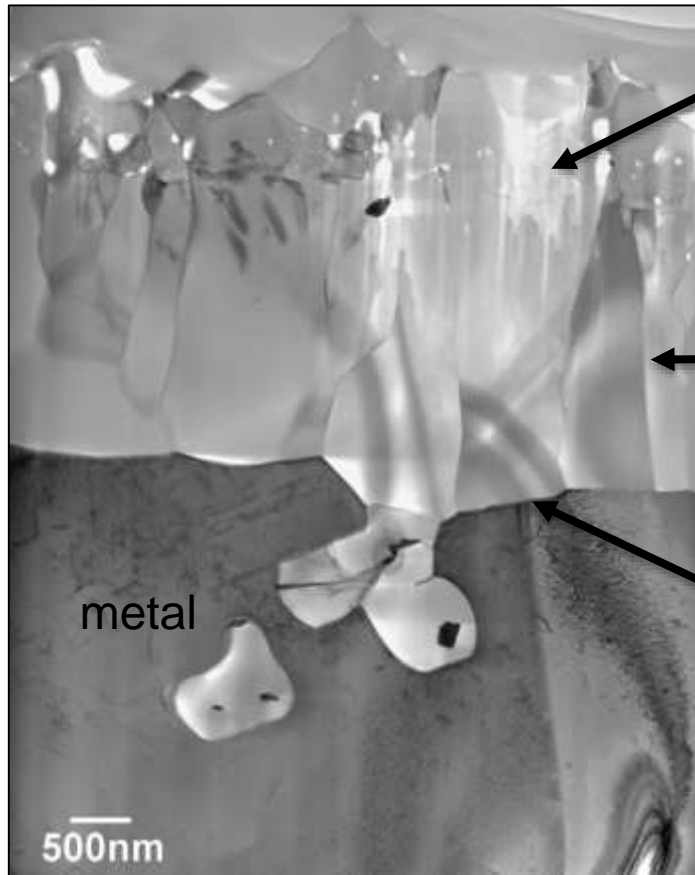
- Protective Ag on top of ridge-GB
- Zr enrichment at GB
- Gibbsian excess Γ_{Zr} : 2.5 nm^{-2}

Overview for NiAl-alloys

- Ni base superalloys are good at high temperatures (e.g. air plane engines)
- Corrosion potentially dangerous
- Stable protective coating (oxide scale) is required: $\alpha\text{-Al}_2\text{O}_3$
- Cr and reactive elements (e.g. Y, Hf) are added to change microstructure of the coating and the chemistry at grain boundaries
- Diffusion of O-ions occurs primarily along oxide grain boundaries (GBs) and can be influenced by additives
- APT can give quantitative information about GB chemistry

Overview: NiAlCr

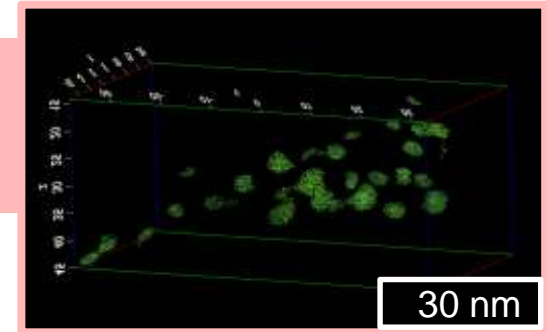
TEM



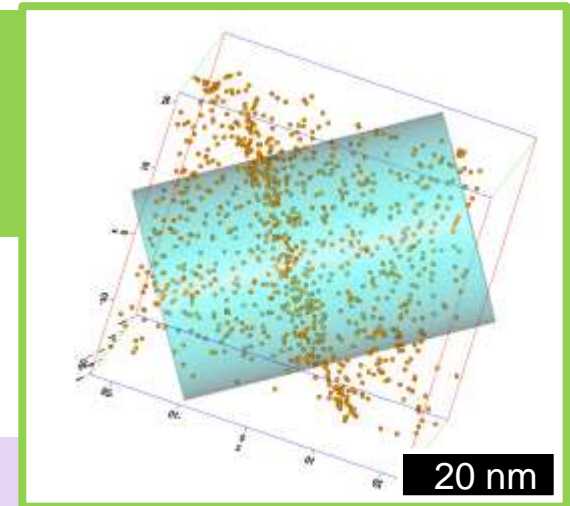
TEM of oxidized NiCrAl after 100h@1100°C

APT

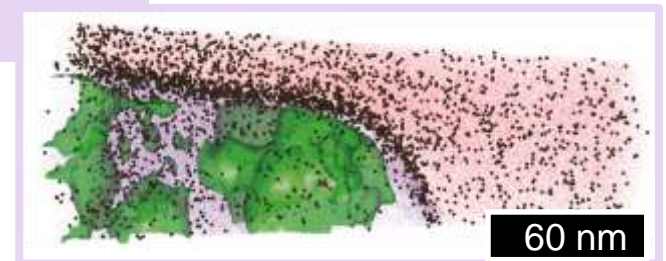
Outer oxide: Phase boundaries (PB) between different oxides



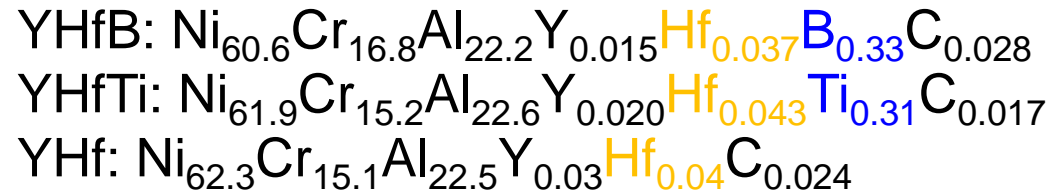
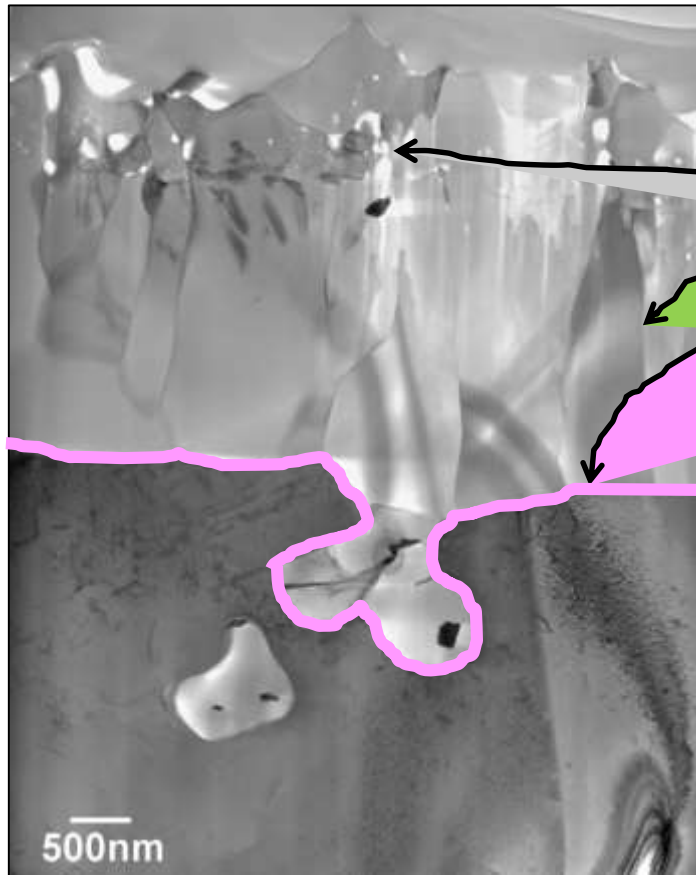
Inner oxide: Grain boundaries (GB) between different Al₂O₃-grains



Phase boundary (PB) between the metal and the Al₂O₃-grains



Overview:TEM



	Metal-Al ₂ O ₃	Al ₂ O ₃ -Al ₂ O ₃	Al ₂ O ₃ -M _y O _x
Hf	Y	Y	Y
Y	N	Y	Y
Ti	N	N	N
B	N	N	N
Ni		Y	
Cr		Y	

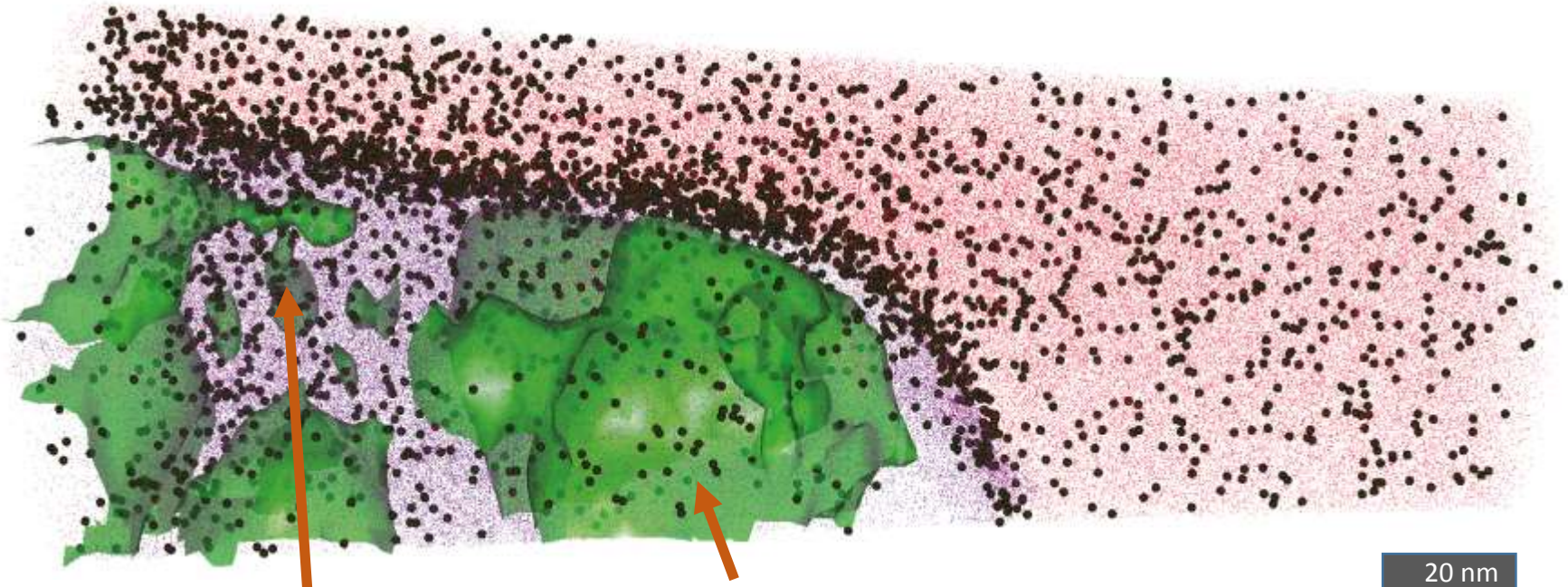
TEM of oxidized NiCrAl after 100h@1100°C

APT: Quantitative enrichment at different interfaces

Atom Probe: YHfTi M/O interface



● HfO
 ● Cr
 ● Ni (isosurface)
 ● Al / AlO



γ : Cr-rich grain
 $\text{Ni}_{59}\text{Al}_{16}\text{Cr}_{24}\text{Ti}_{0.1}$

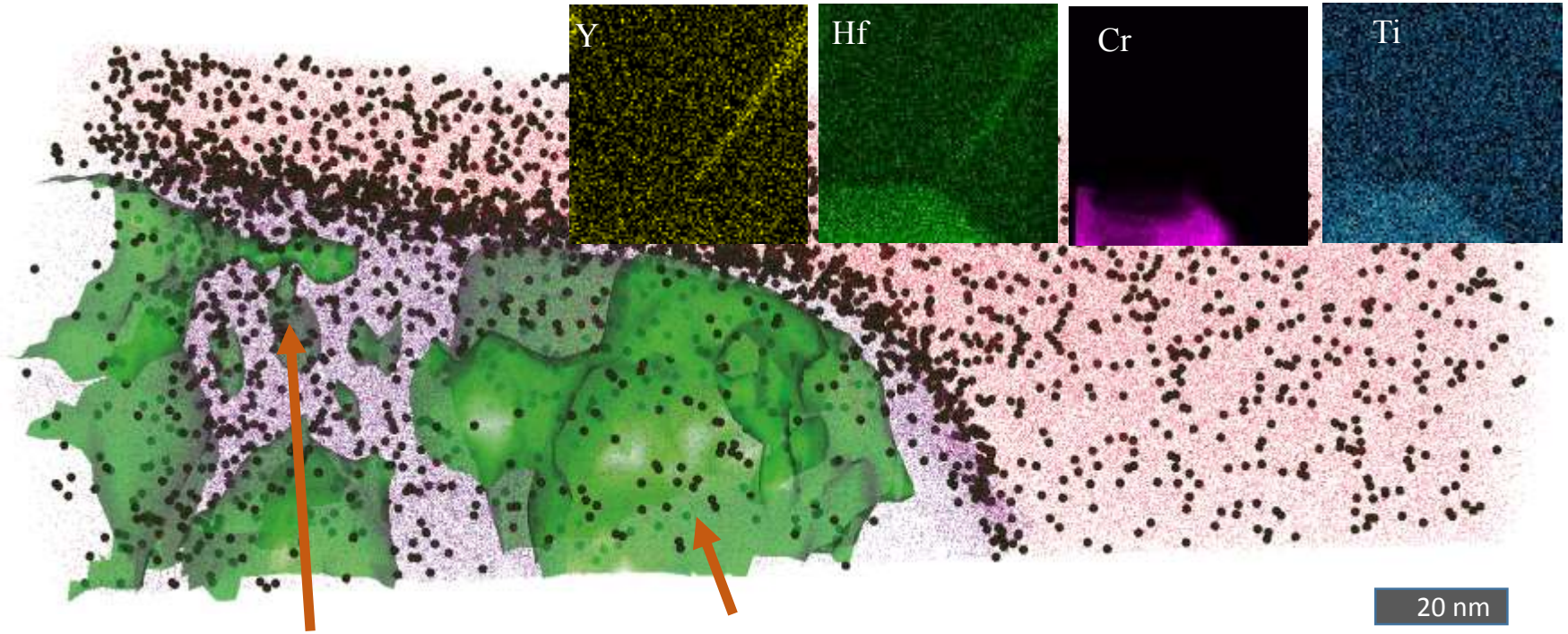
γ' : Al-rich grain
 $\text{Ni}_{70.2}\text{Al}_{21.3}\text{Cr}_{5.9}\text{Ti}_{0.7}$

- Hf but no Ti or Y at metal-oxide interface
- γ/γ' metal nanosructure. Ti is enriched in γ'

Atom Probe: YHfTi M/O interface



● HfO
 ● Cr
 ● Ni (isosurface)
 ● Al / AlO

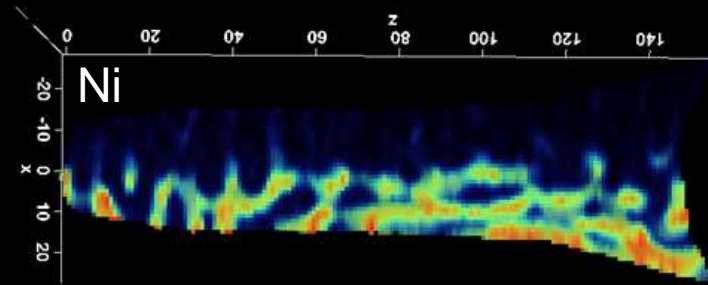
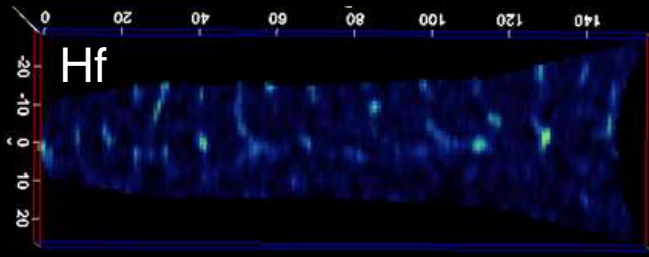
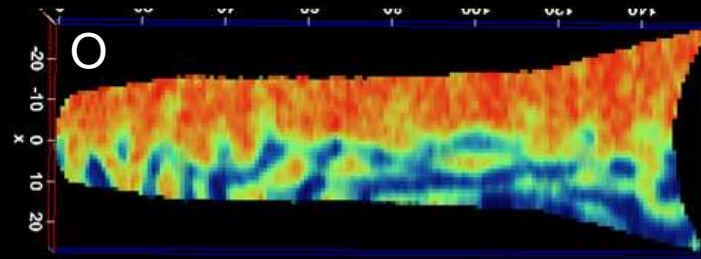
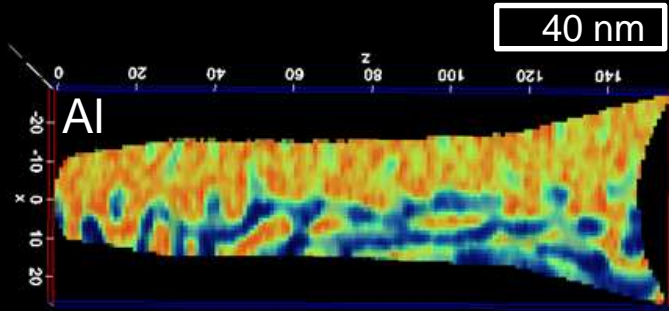


Cr-rich grain
 $Ni_{59}Al_{16}Cr_{24}Ti_{0.1}$

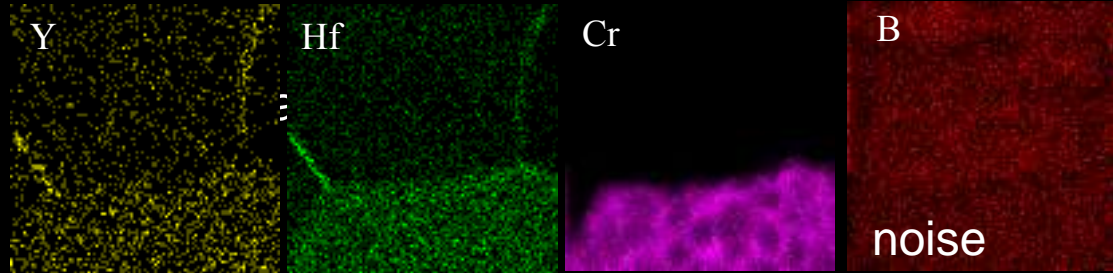
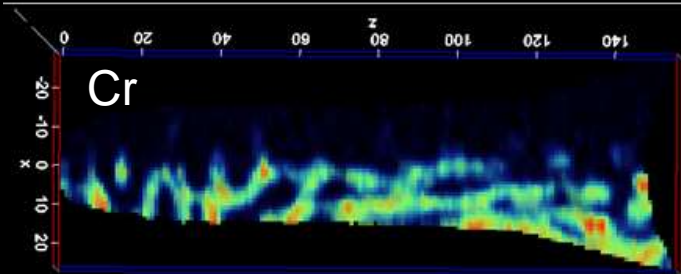
Al-rich grain
 $Ni_{70.2}Al_{21.3}Cr_{5.9}Ti_{0.7}$

- Hf but no Ti or Y at metal-oxide interface
- γ/γ' metal nanosructure. Ti is enriched in γ'

Atom Probe: YHfB: Metal-oxide interface

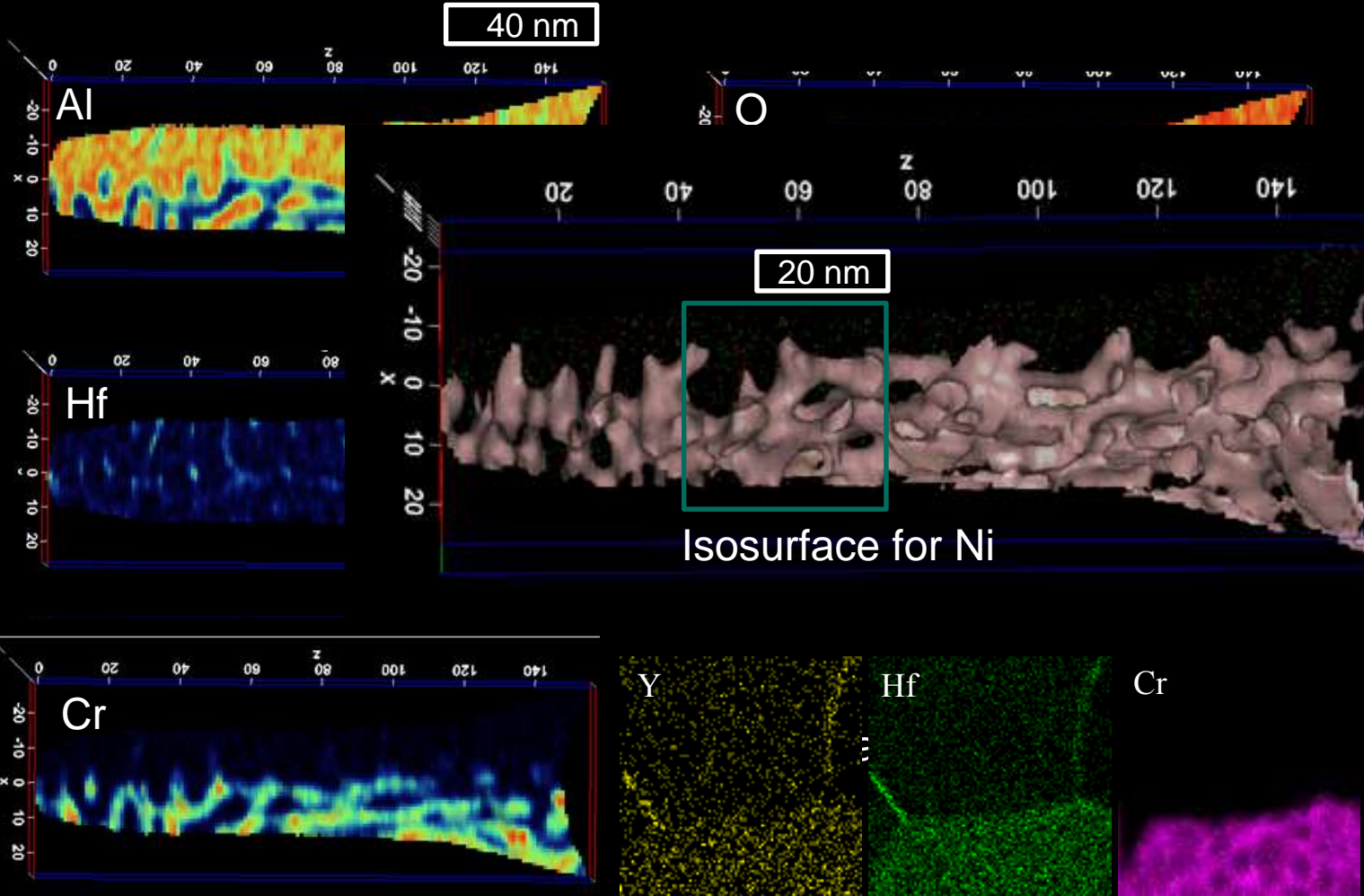


at. %
Ni 0-66
Al 6-55
Cr 0-33
O 5-55
Hf 0-22
Ga 0-18



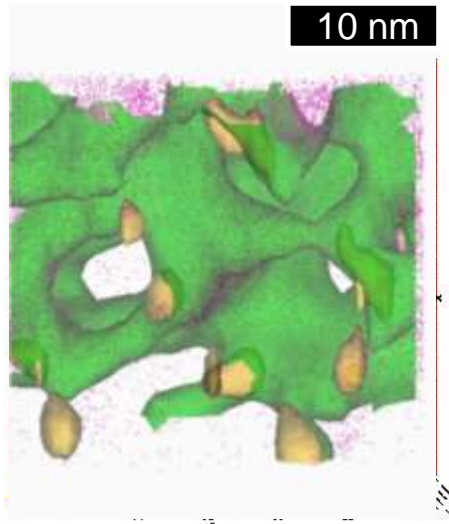
Unexpected interface roughness

Atom Probe: YHfB: Metal-oxide interface

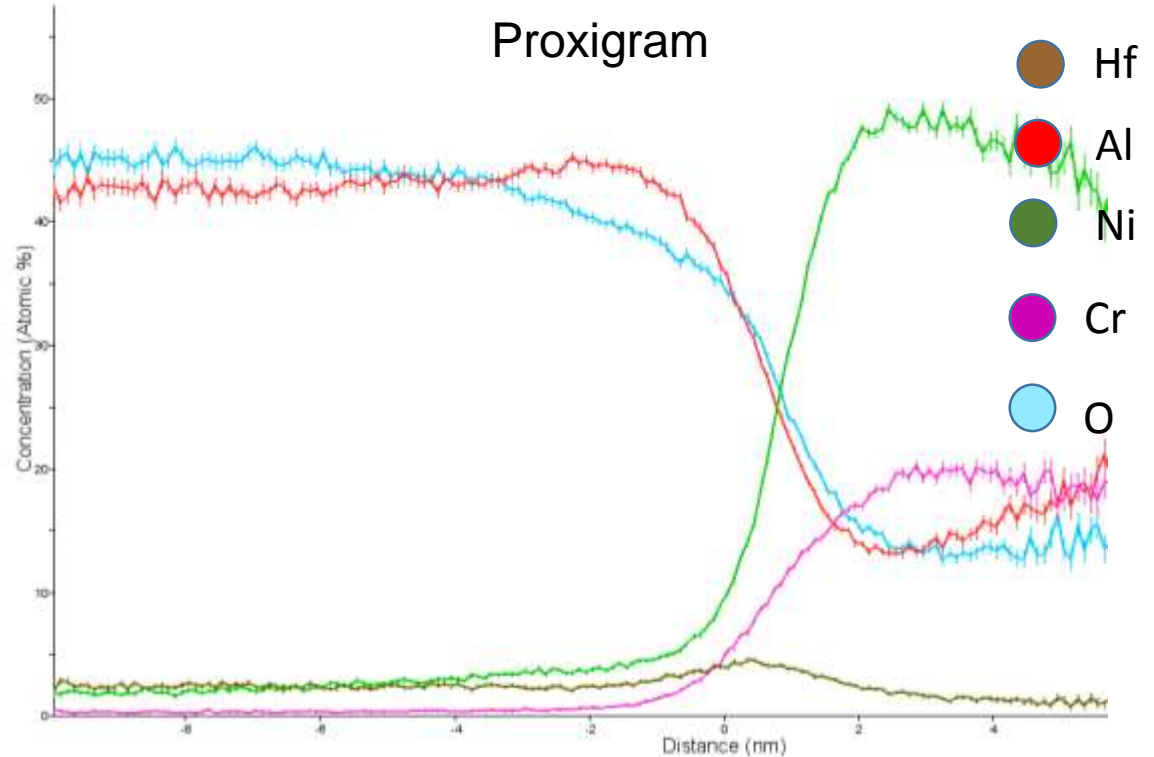


Unexpected interface roughness

M/O interface

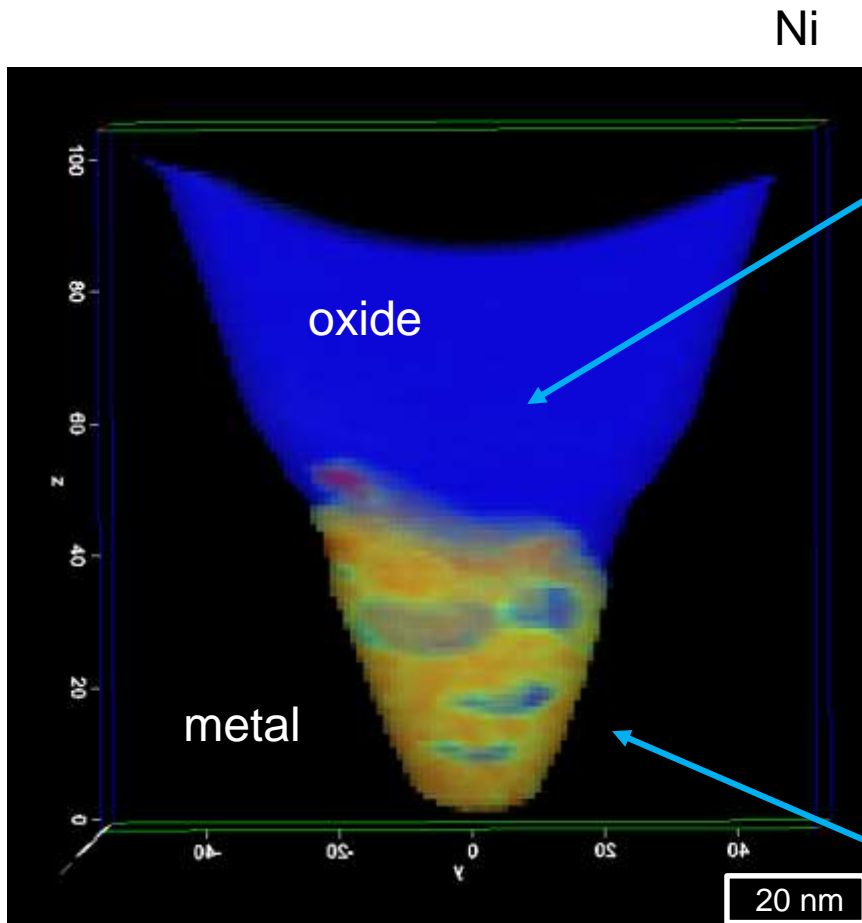


Green: 17 at.% Ni
brown: 2at.%Hf



- Al_2O_3 interface
- Al depleted, Ni enriched in the metal close to the interface
- Hf enriched at interface
- Nothing else is enriched at the interface

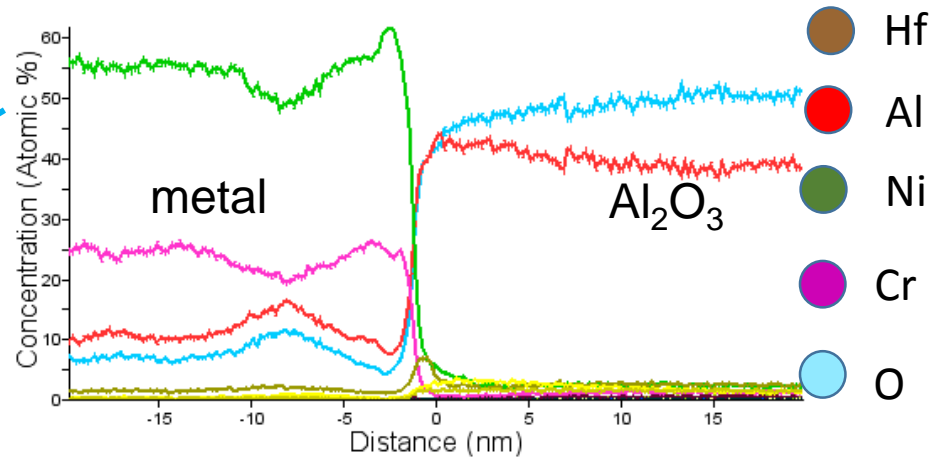
APT: YHfB- M/O-interface: non stoichiometric AlO in metal



Particles not stoichiometric Al_2O_3

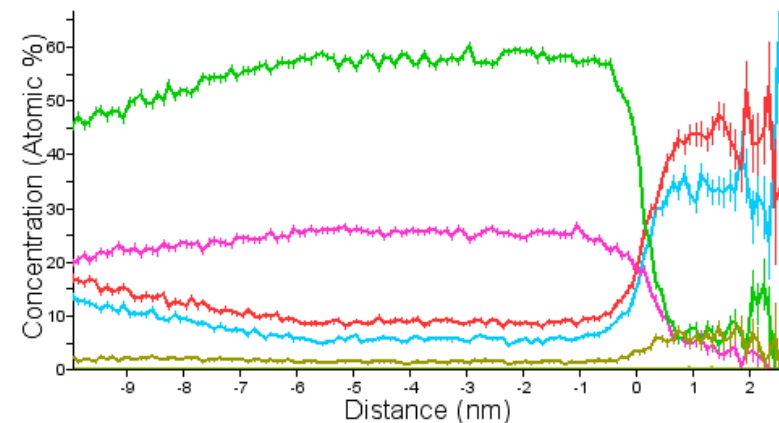
Isosurface 34 at.% O

Proxigram - Interface 6



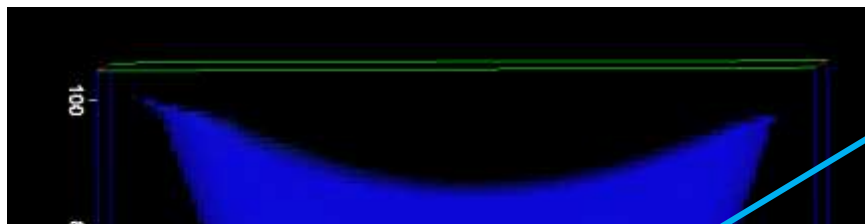
Isosurfaces 13 at.% O

Proxigram - Interfaces: 0, 1, 3, 5



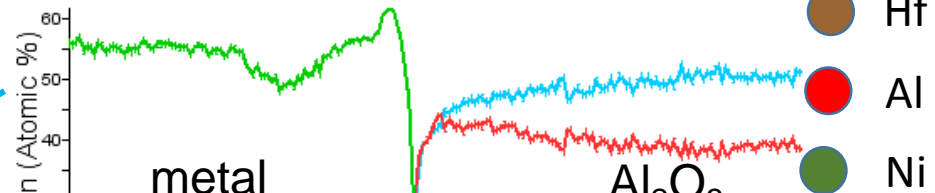
APT: YHfB- M/O-interface: non stoichiometric AlO in metal

Ni



Isosurface 34 at.% O

Proxigram - Interface 6

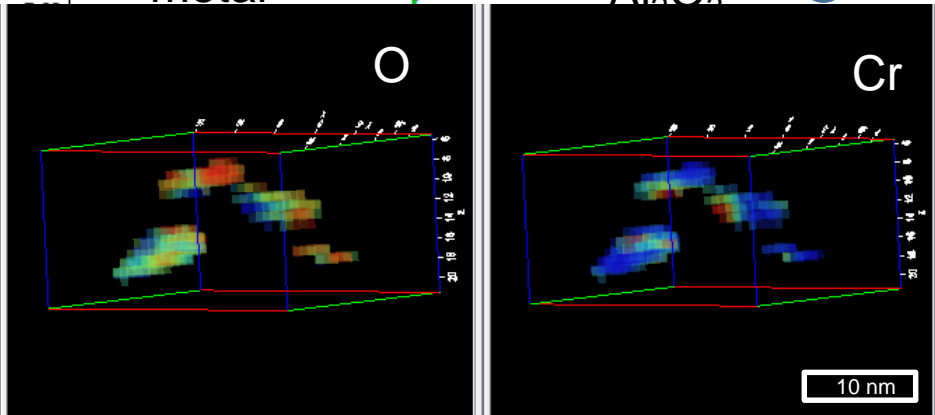
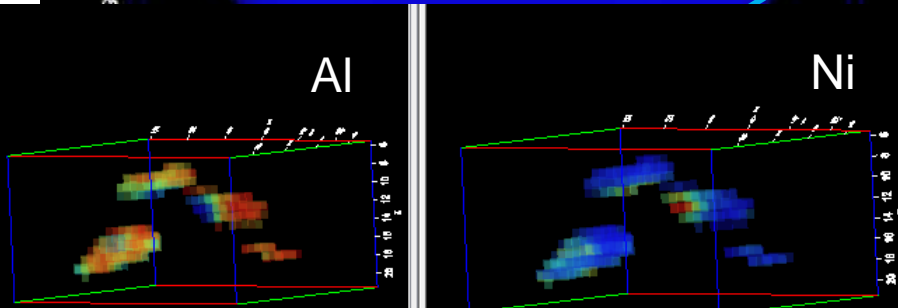


Al

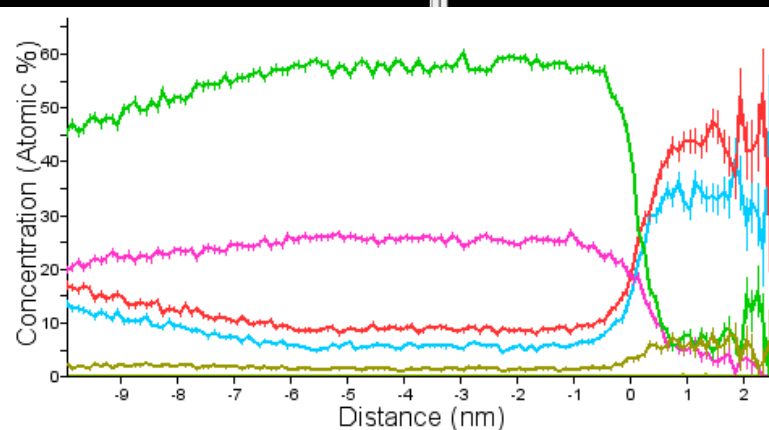
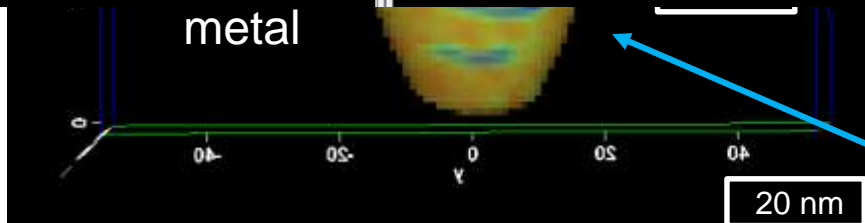
Ni

O

Cr



metal



Particles not stoichiometric Al_2O_3 but contain NiO and CrO

Conclusions I

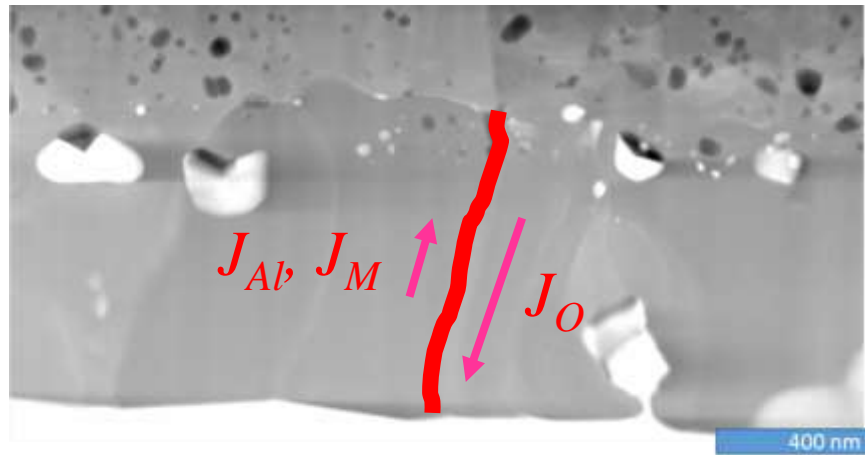
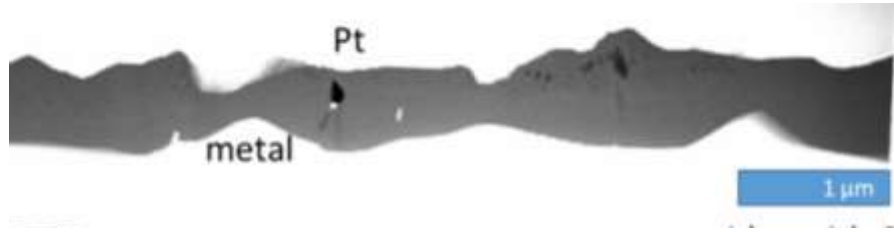
■ The solutes

- Ti not found at phase or grain boundaries
- Hf segregates to metal/oxide PBs, oxide/oxide PBs and oxide GBs
- Y segregates to oxide/oxide GBs and PBs but not to metal-oxide PBs
- B shows no segregation to PBs or GBs
- Al_2O_3 - Al_2O_3 GBs contain Ni and Cr
- Hf and Y could influence the transport of O, Ni and Cr in these GBs

■ The oxidation progress

- Rough oxide/metal interface
- Oxidation in the metal progresses along γ/γ' -PBs into Al-rich γ' -phase
- Small oxides in metal are not stoichiometric Al_2O_3
- Only observed due to APT

Outward diffusion in oxide scale on NiAl



- Protective Al_2O_3 coating on NiAl-alloy
- O (and all other elements) in α -alumina diffuse mostly via grain boundaries (GBs)
- Minor outward diffusion of metal
- Decoration of GBs will influence the diffusion and thus oxidation
- Apparently grows inwards

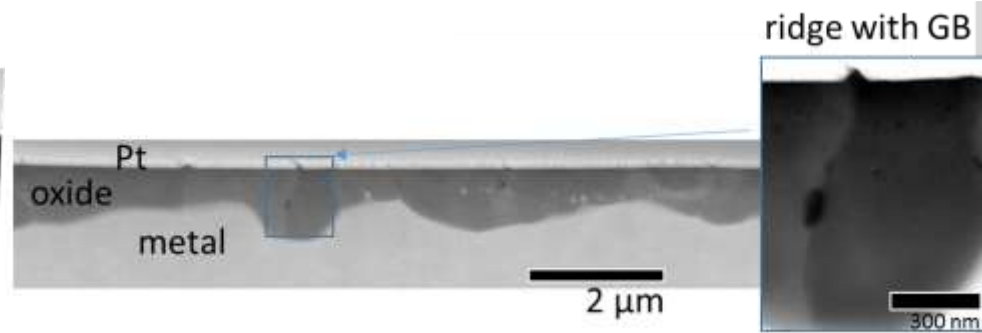
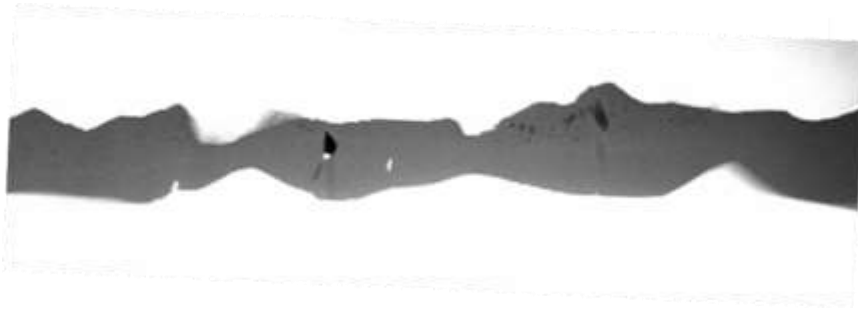
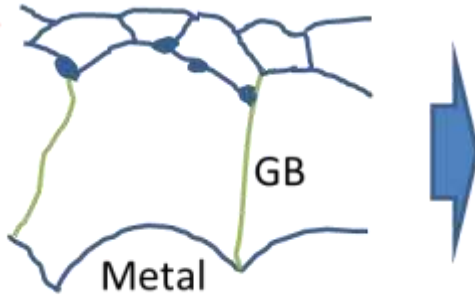
Material	Ni at.%	Al at.%	Zr ppma	Hf ppma	N ppma	C ppma	Sxx ppma	O ppma	B ppma	Cr ppma
Zr-doped	49.95	49.99	520	0	0	0	3	48	30	0
Hf-doped	49.83	50.07	0	480	30	36	0	43	0	100

Outward diffusion: Exp. idea

a) After 1st exposure

small grains
+ voids

large Al₂O₃
grains

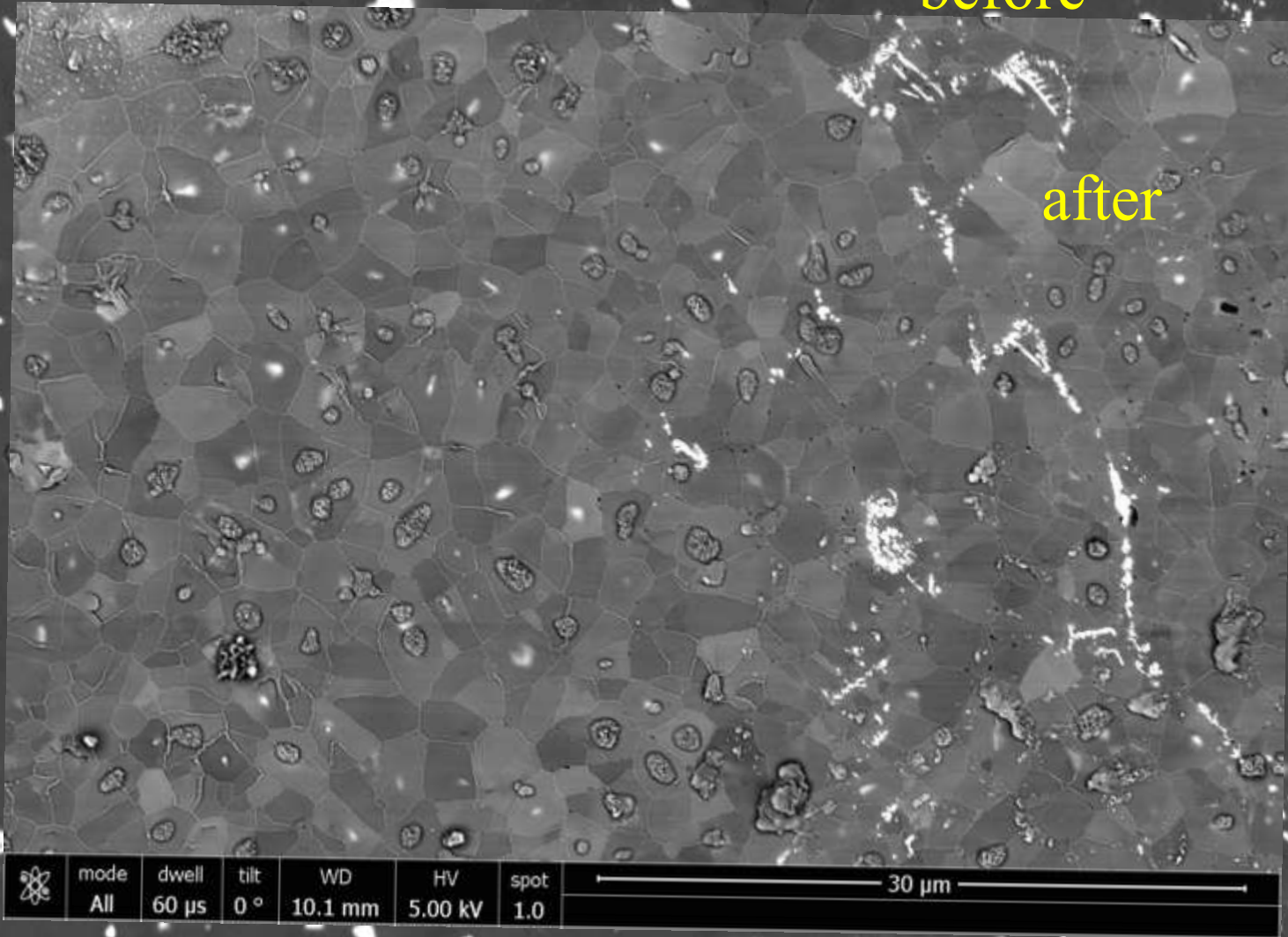


Outward diffusion: SEM

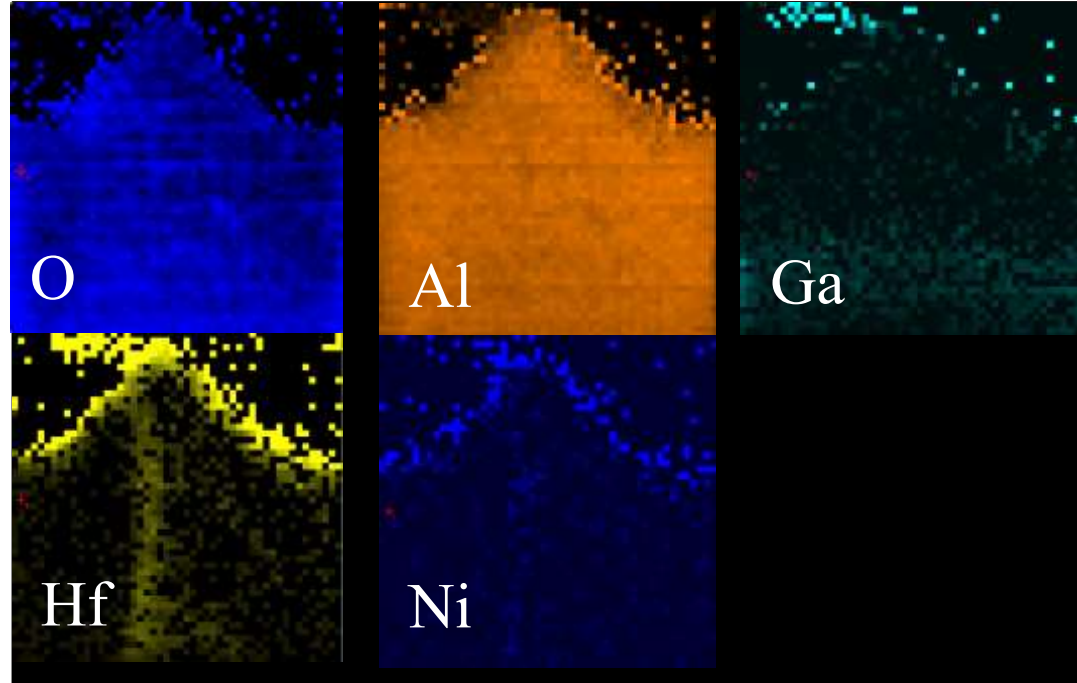
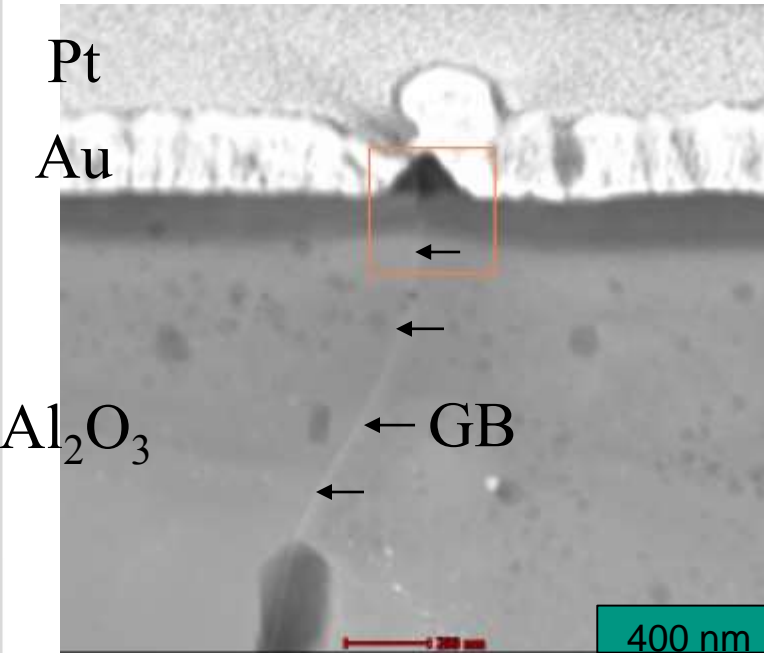
Hf 10h exposure

before

after

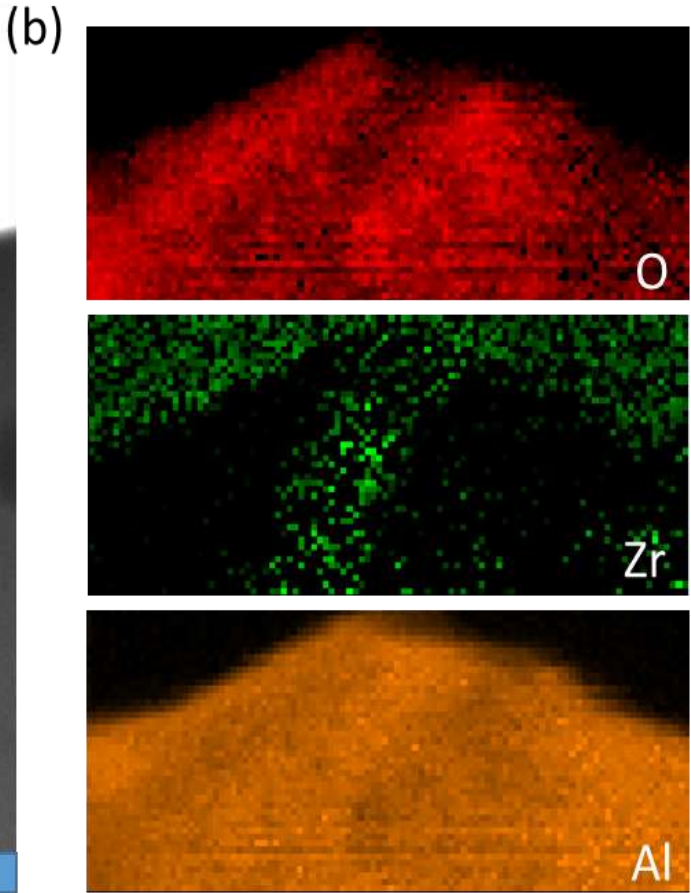
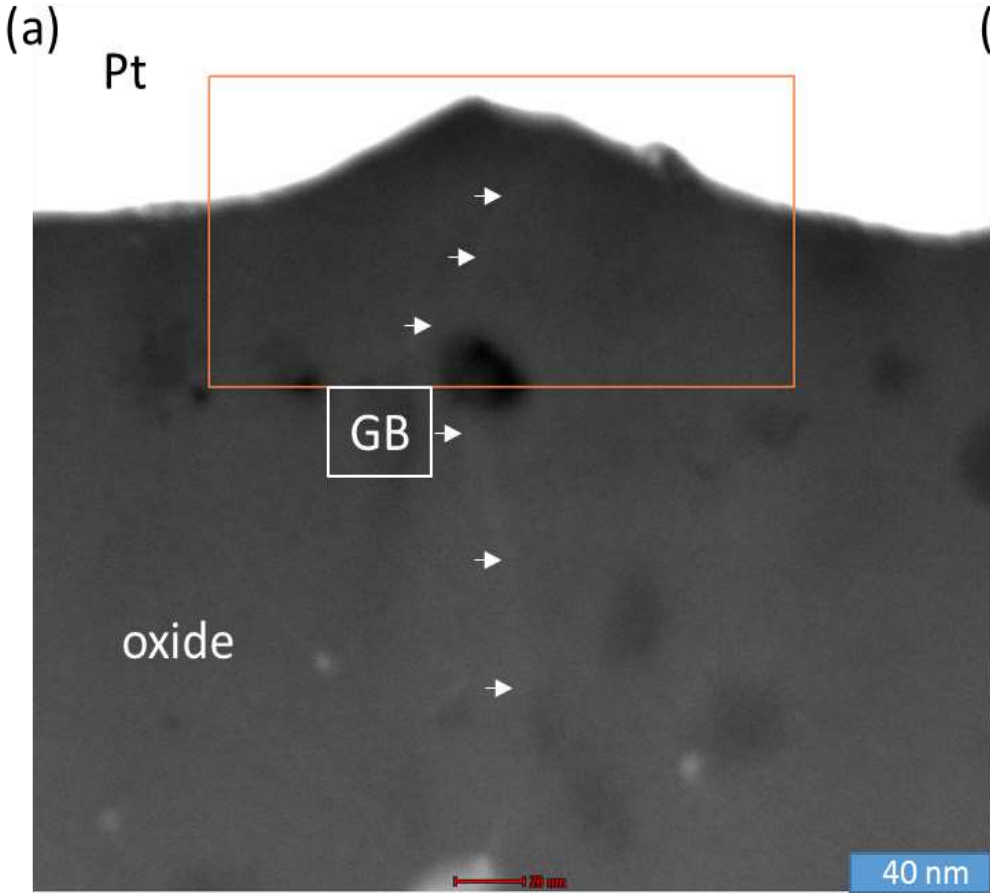


TEM of mechanically polished Hf sample



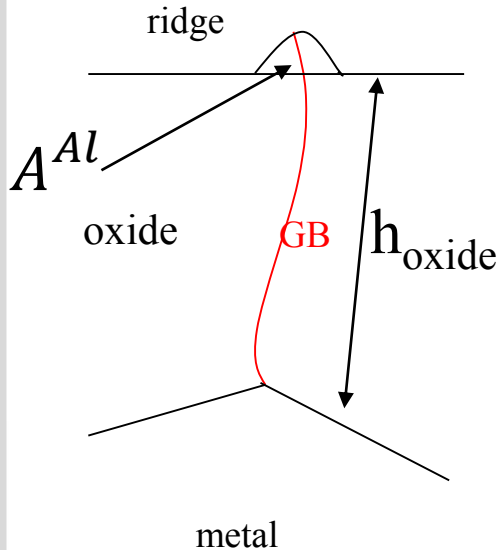
- No Ga contamination
- GB enriched with Hf and some Ni

TEM of Zr sample



Zr enriched at the GB

How to calculate the flux



- Calculate the flux
 - Number of diffused Al-atoms N_{GB}^{Al}
 - Exposure time Δt (10h)

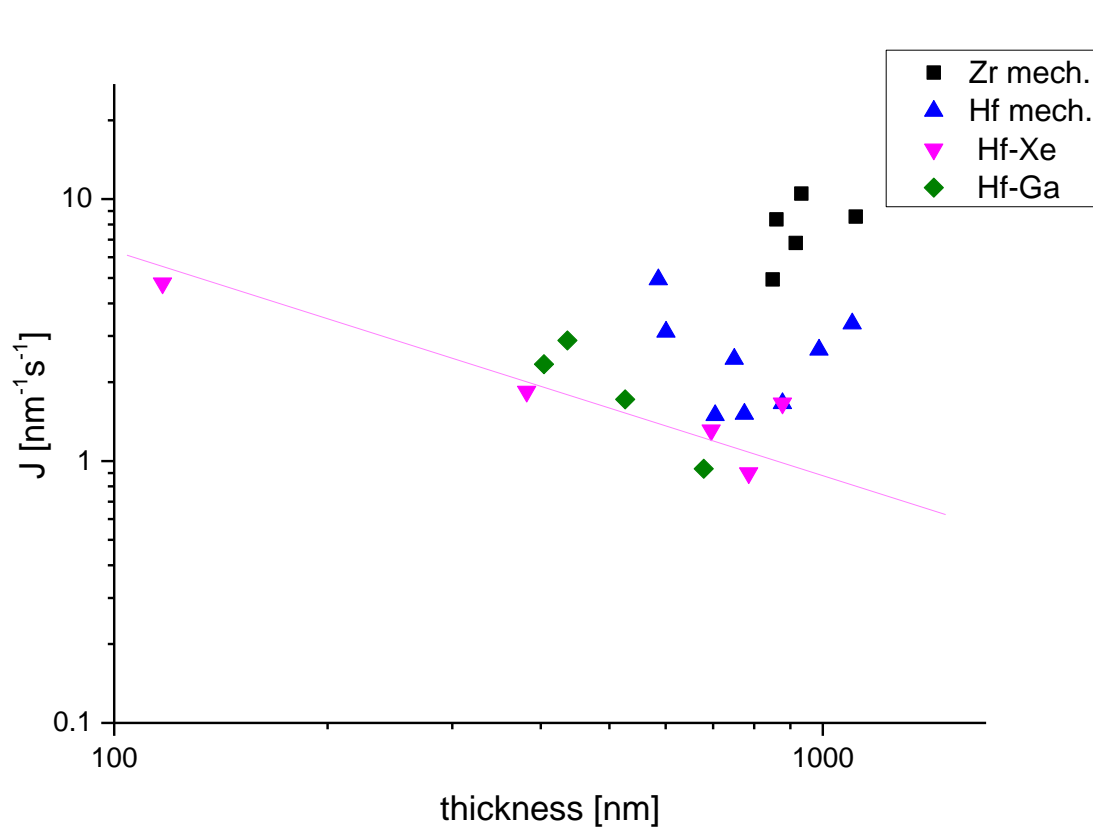
- Calculate number of atoms
 - Volume of ridge $V^{\text{Al}} = A^{\text{Al}} L_{GB}$
 - Length of GB L_{GB} (not height!)
 - Cross section area of ridge A^{Al}
 - Volume of Al_2O_3 unit cell: $V_u = 2.54 \cdot 10^{-22} \text{ cm}^3$
 - Number of Al atoms per unit cell: 12

$$J_{\text{Al}} = \frac{N_{GB}^{\text{Al}}}{L_{GB} \Delta t}$$

$$N_{GB}^{\text{Al}} = \frac{12 V^{\text{Al}}}{V_u}$$

$$J_{\text{Al}} = \frac{12 A^{\text{Al}}}{V_u \Delta t}$$

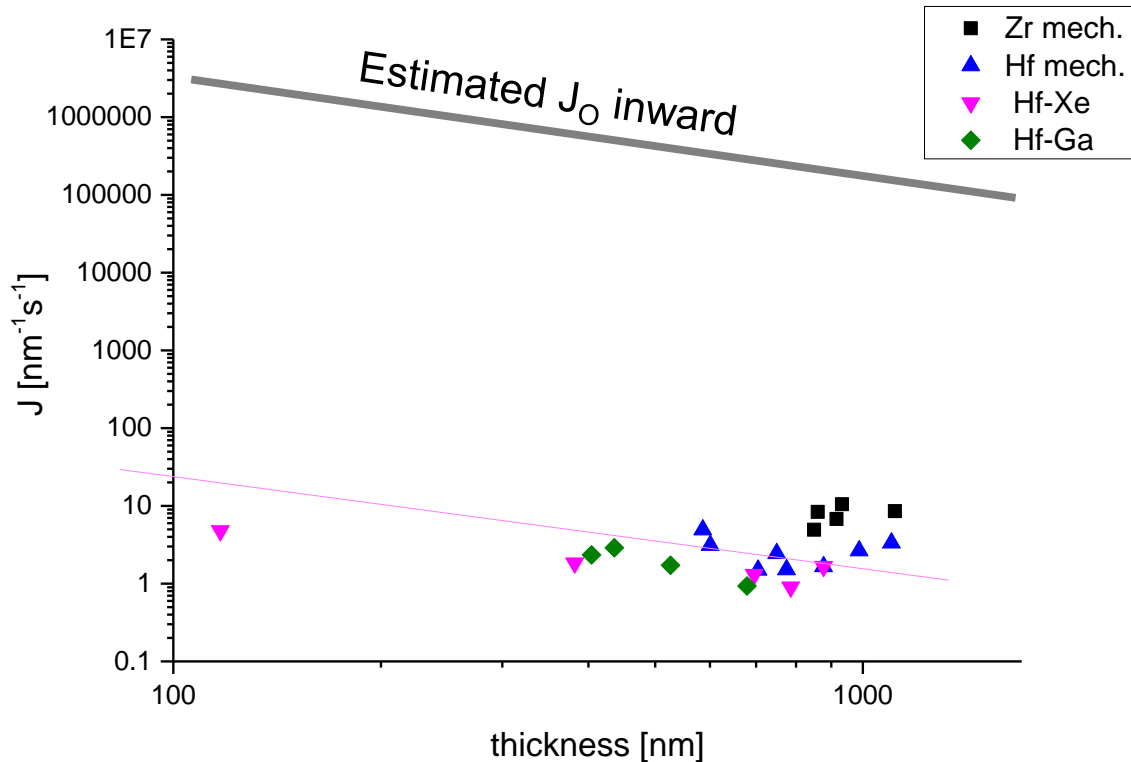
Flux of Al through GBs at 1100° C



- Mechanical polishing enhances ridge growth
- Zr allows higher outward flux than Hf

follows Fick's 1st law

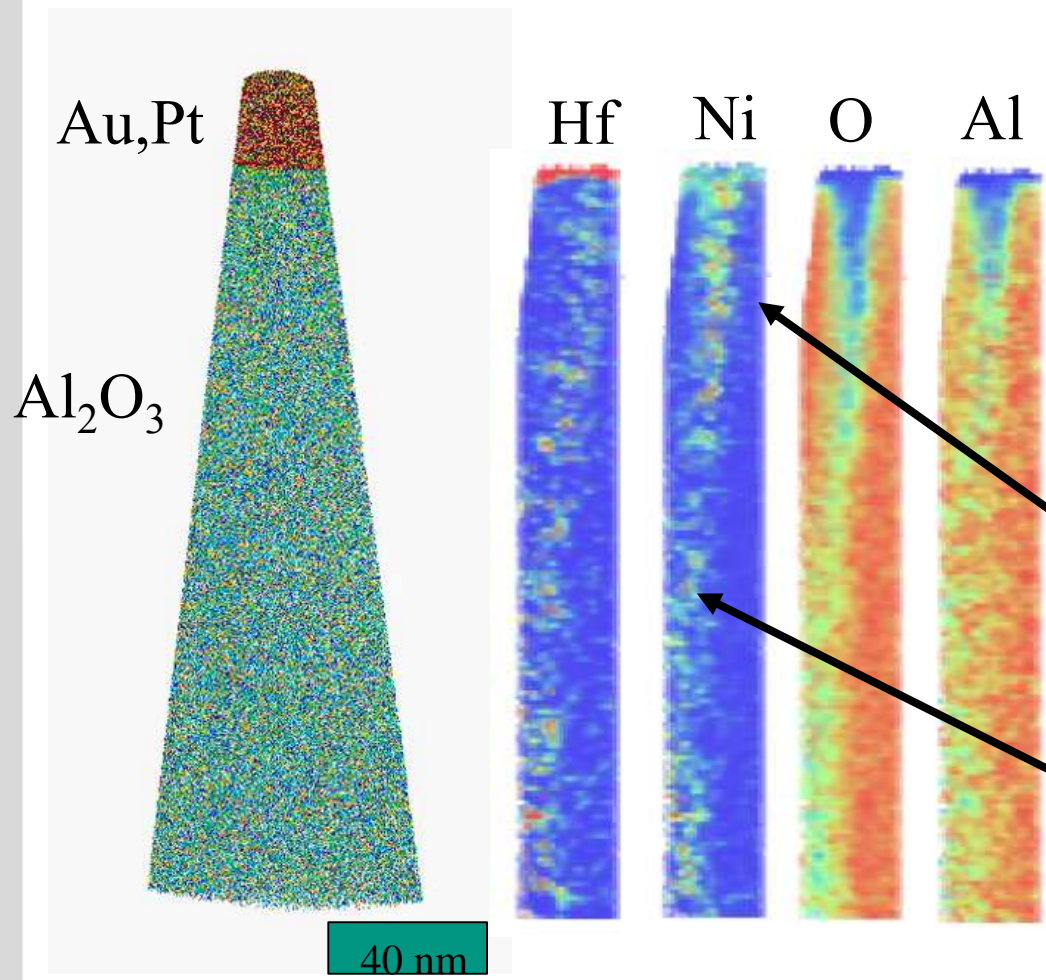
Flux of Al through GBs at 1100° C



- Mechanical polishing enhances ridge growth
- Zr allows higher outward flux than Hf
- Inward flux six orders of magnitude larger

follows Fick's 1st law

APT of NiAl + Hf sample

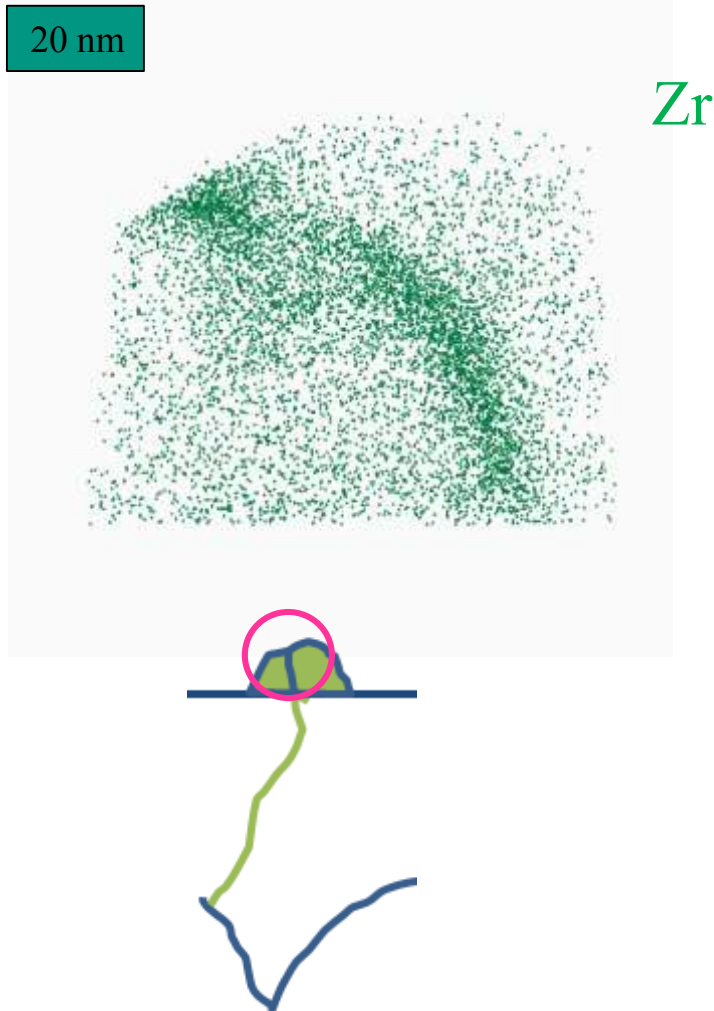


- Protective Au,Pt coating
- GB with Hf, Ni
- Ni enriched at surface
- Gibbsian excess Γ
(Number of additional atoms per area in GB):

Hf: 0.5 nm^{-2}
Ni: 2.6 nm^{-2}

Hf: 0.35 nm^{-2}
Ni: 0.59 nm^{-2}

APT of NiAl + Zr sample: At the ridge

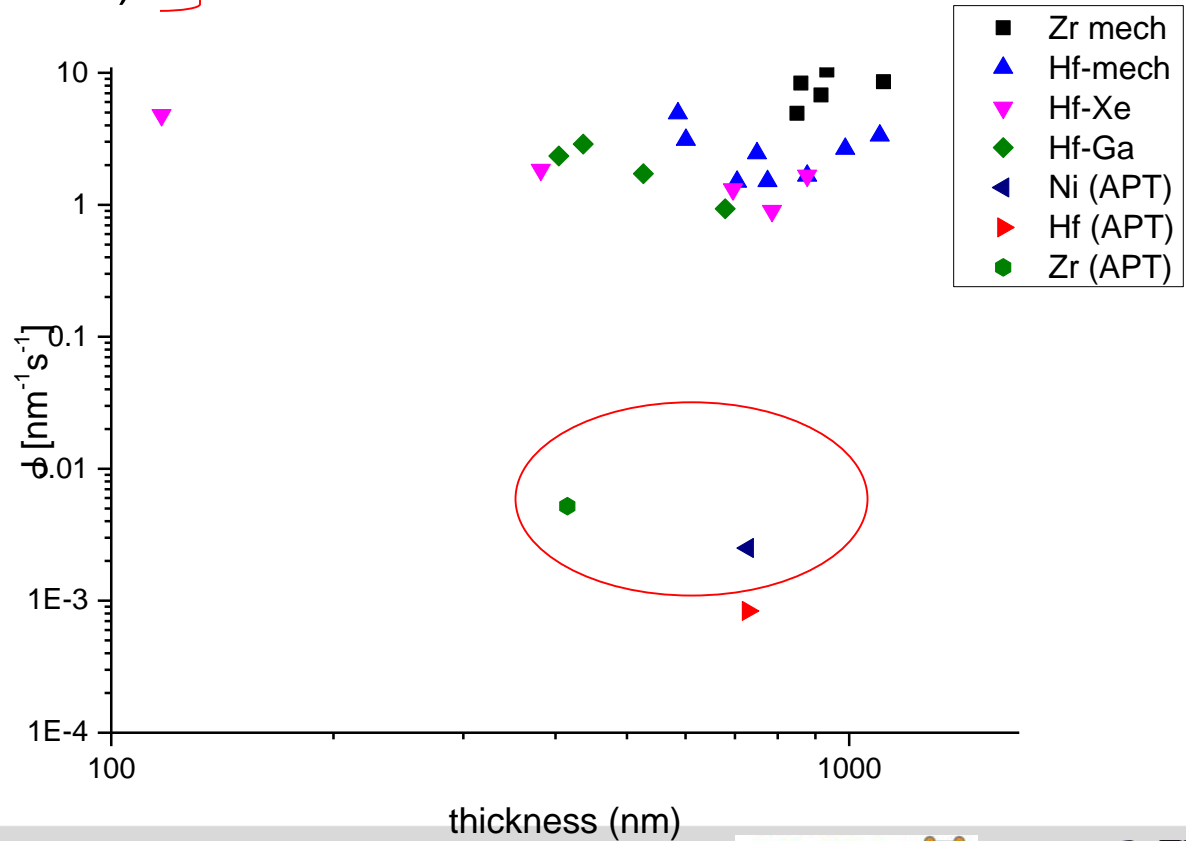
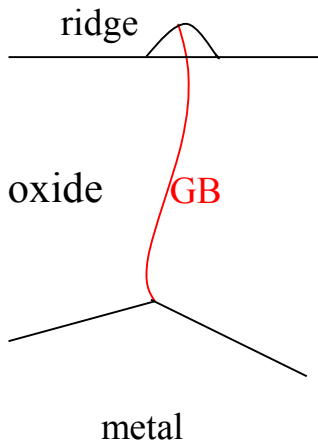


- Protective Ag on top of ridge-GB
- No Ni found
- Γ_{Zr} : 2.5 nm^{-2}

Outward flux of Ni, Hf, Zr

- Outward flux into ridge GB
- Gibbsian excess
- Additional GB length (ridge height from SEM)
- $J_X = \Gamma_X h_{\text{ridge}} / \Delta t$

→ amount of diffused material

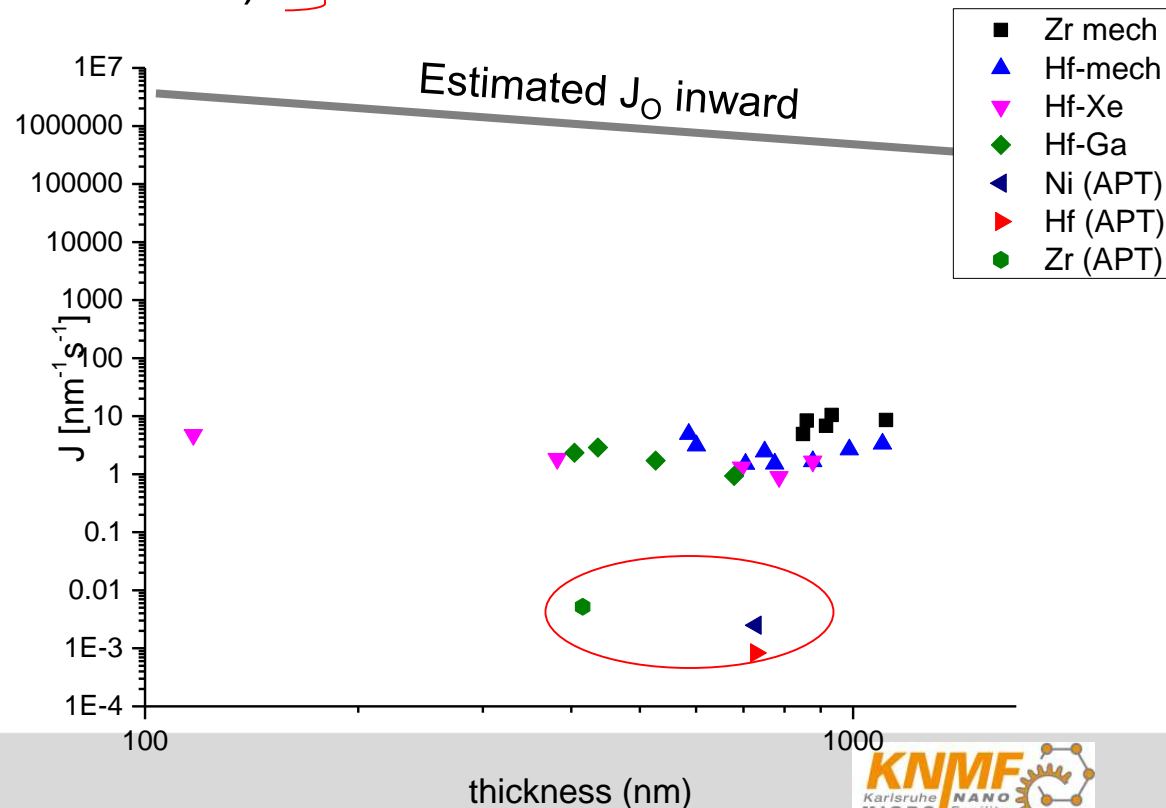


Outward flux of Ni, Hf, Cr

- Outward flux into ridge GB
- Gibbsian excess
- Additional GB length (ridge height from SEM)
- $J_X = \Gamma_X h_{\text{ridge}}$

→ amount of diffused material

$$J_O \gg J_{Al} \gg J_{Hf, Ni, Zr}$$



Conclusions II

- **Outward Diffusion of Al** along Al_2O_3 GBs is observed by STEM
Mechanical polishing introduces defects that promote diffusion
 - Hf reduces Al-outward diffusion stronger than Zr
- Zr is enriched at GBs → **Outward diffusion of Zr, Hf**
- Hf is enriched at GBs
- Ni is found at the GB and at the top of the ridge in the Hf sample → **Outward diffusion of Ni**
- $J_{\text{O}} \sim 10^6 \text{ nm}^{-1}\text{s}^{-1} \gg J_{\text{Al}} \sim 1 \text{ nm}^{-1}\text{s}^{-1} \gg J_{\text{Hf,Ni,Zr}} \sim 10^{-3} \text{ nm}^{-1}\text{s}^{-1}$

Atom Probe Tomography: fast facts

- Small tip ($d < 400$ nm), high field (10-50 V/nm) in UHV \rightarrow atoms almost field evaporate
- Additional event: Laser /voltage \rightarrow evaporate single atoms
- Evaporation time and arrival time \rightarrow time of flight mass spectrometer \rightarrow elements and molecules can be identified
- Detection on a 2D detector \rightarrow (x,y)-position of atom
- Z-position from arrival sequence
- APT can analyze (in order of difficulty): metallic alloys, semi-conductors, multi-layer systems, ceramics, non-organic compounds; organic materials are problematic
- Atomic resolution for a volume of 20-300 nm in diameter and 20-2000 nm in length

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Thank you for your attention

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